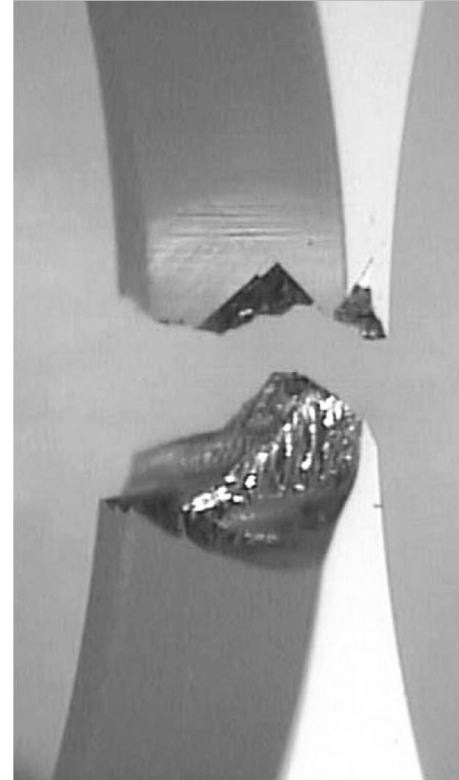
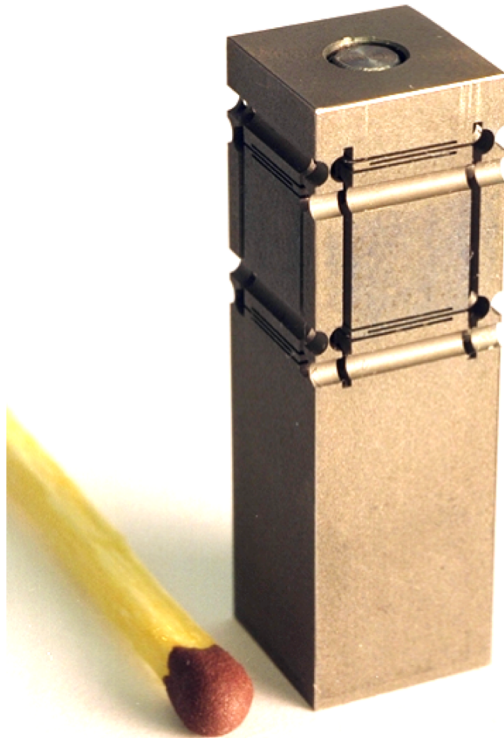


TECHNOLOGICAL ASPECTS



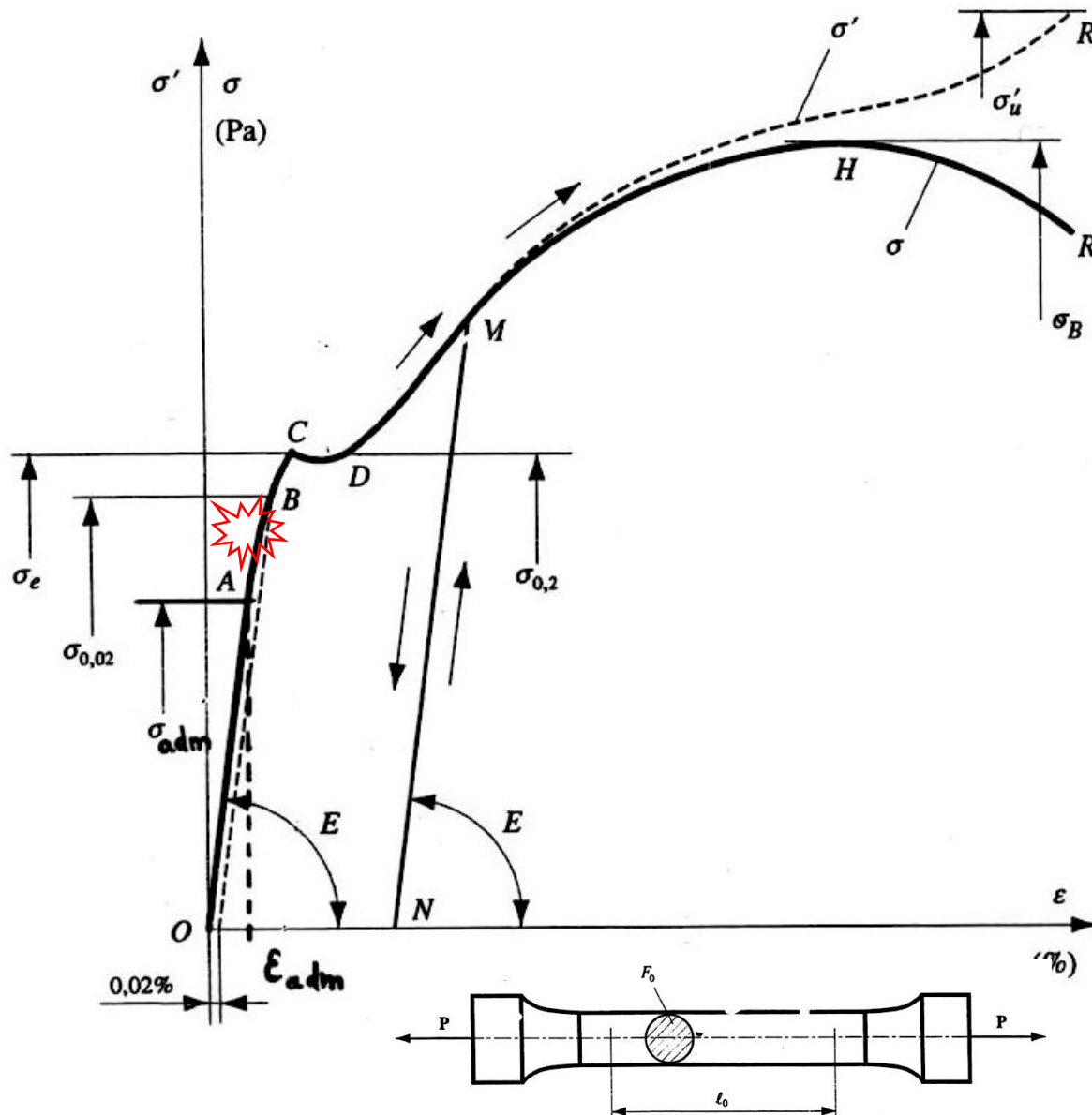
Prof. Simon Henein, Dr. Etienne Thalmann

Material selection

Strain $\epsilon = \frac{\Delta l}{l}$

Stress $\sigma = \frac{P}{F}$

Hook's Law $\epsilon = \frac{\sigma}{E}$



The stroke of flexures is proportional to:

$$\frac{\sigma_{adm}}{E}$$

← Admissible stress

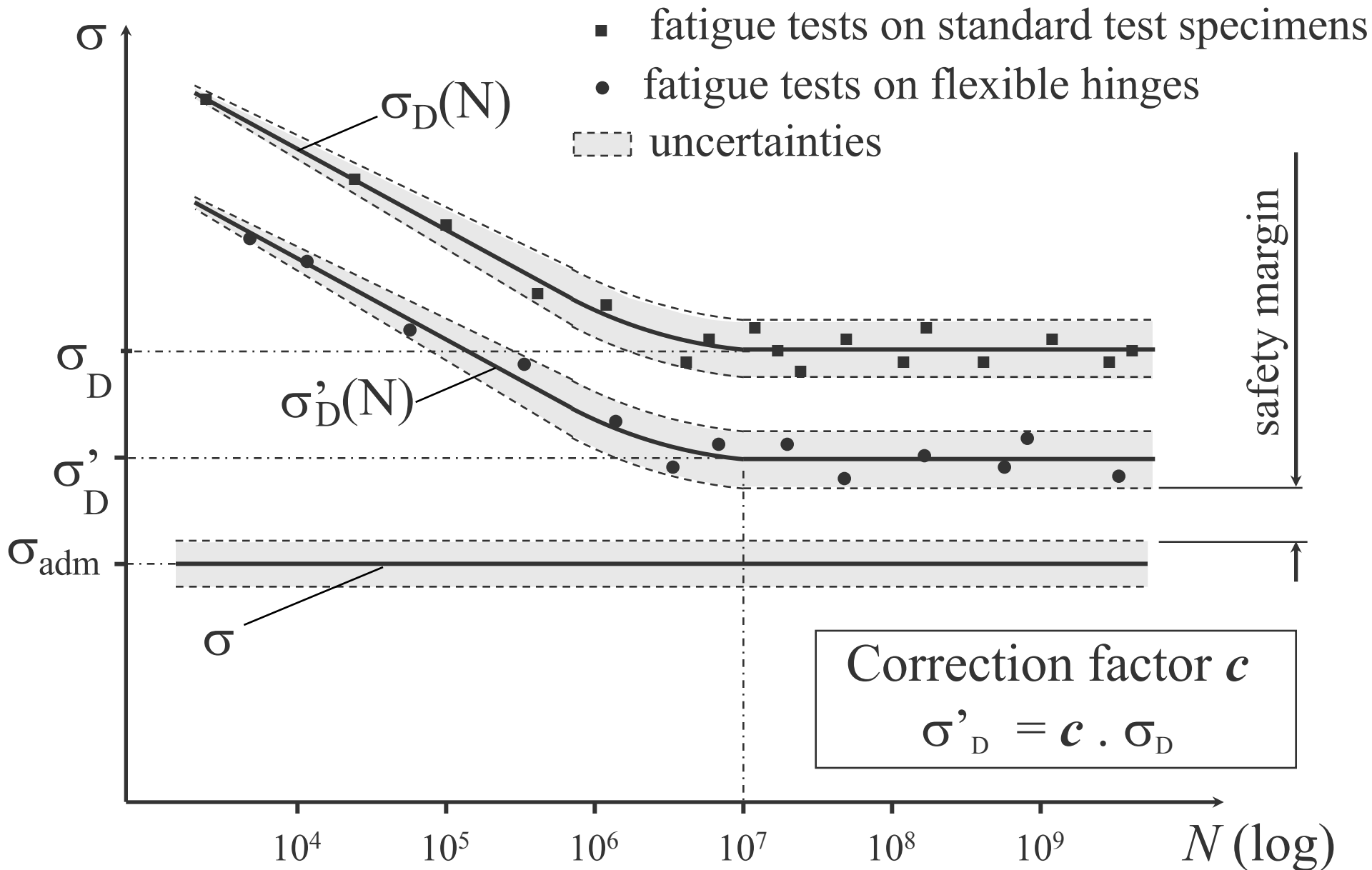
← Young's Modulus

« Materials that are good for springs, are good for flexures »

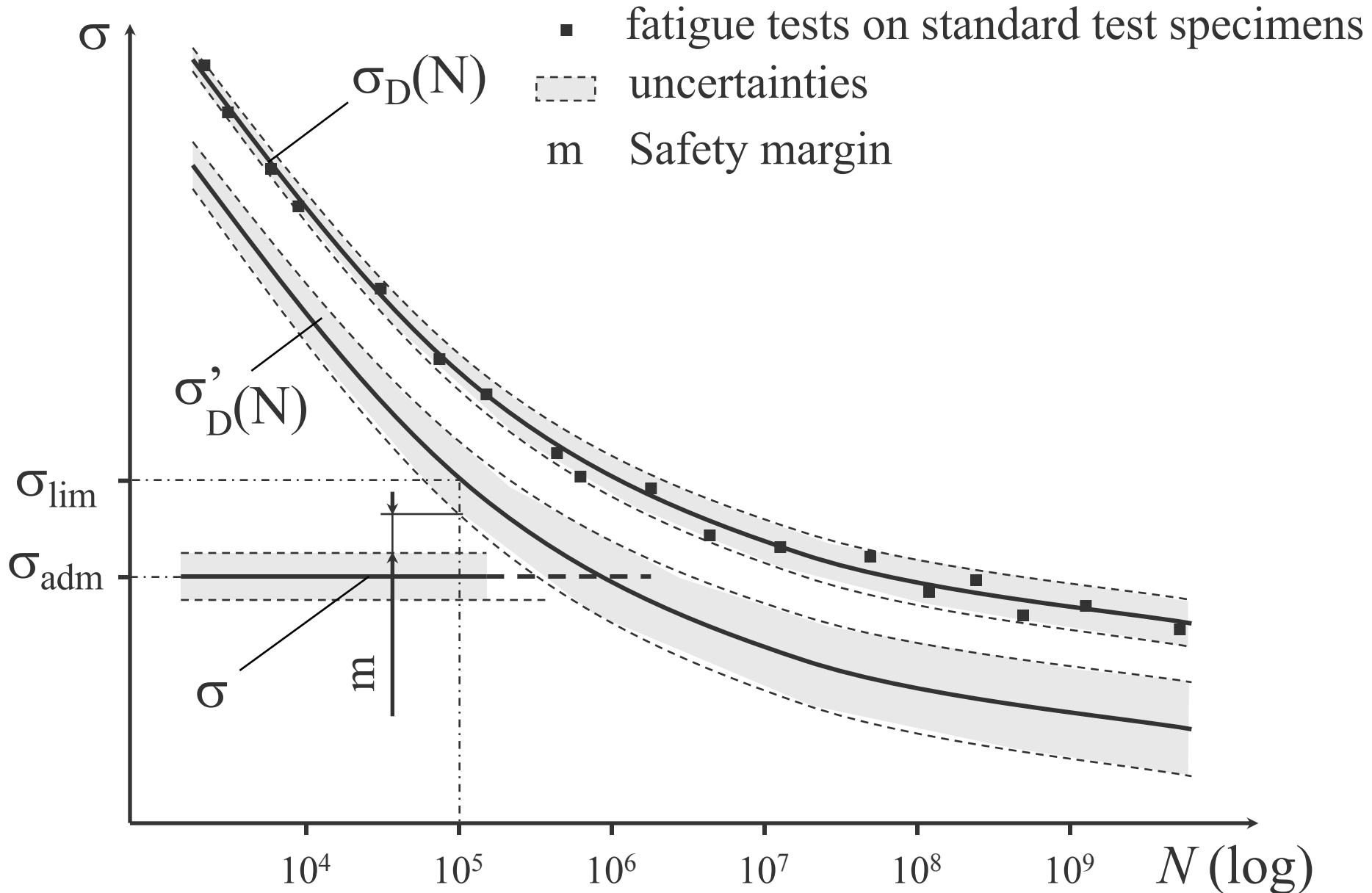
Commonly used metallic alloys

- Spring steels, carbon steels
e.g. X220CrVMo13-4 (K190), X3NiCoMoTi18-9-5 (W720)
- Spring stainless-steels
e.g. X10CrNi18-8, N700 ESU (17-4 PH)
- Titanium alloys
e.g. Ti Al6 V4
- Copper-beryllium alloys
e.g. XHMS
- Bronze alloys
e.g. Cu Ni 15 Sn 8
- Aluminum alloys
e.g. AlCuSiMn (Avional), AlZnMgCu1.5 (Perunal)

Fatigue theory



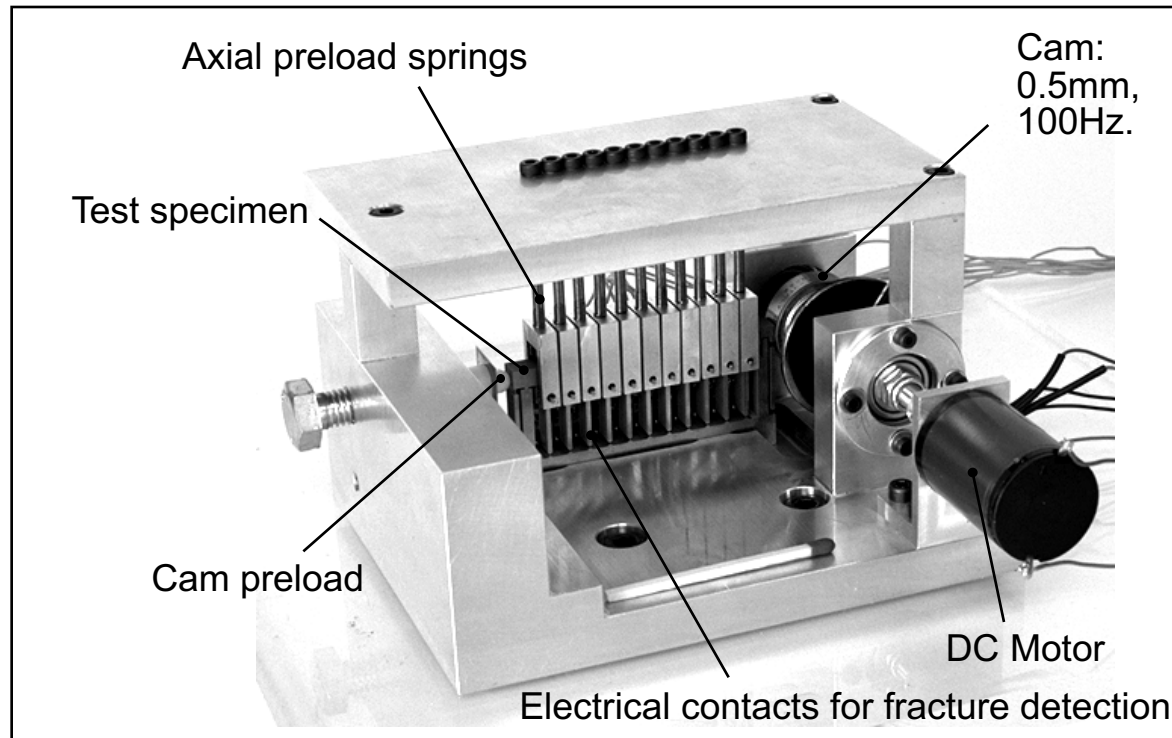
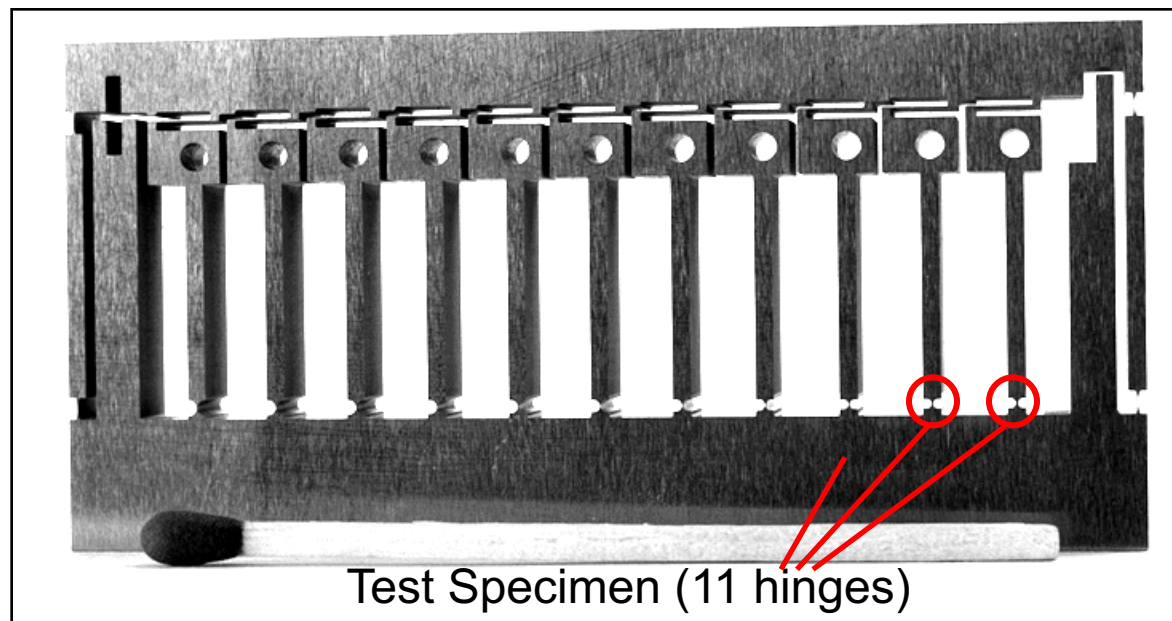
Fatigue of materials without fatigue plateau (e.g. Alu)



Fatigue tests

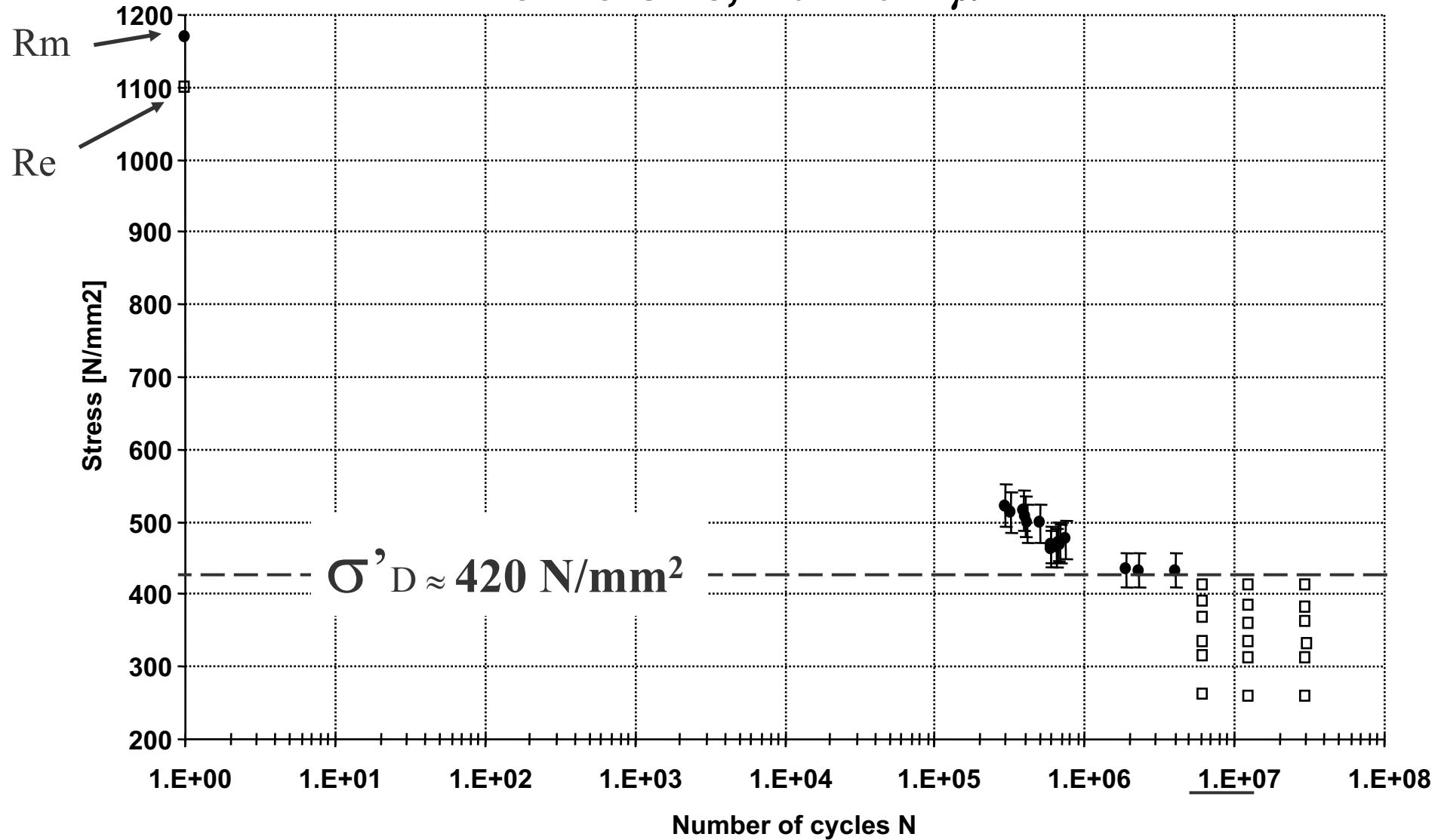
Studied parameters:

- Comparison with data for the bulk material
- Effect of EDM process
- Effect of surface roughness
- Effect of stress concentrations



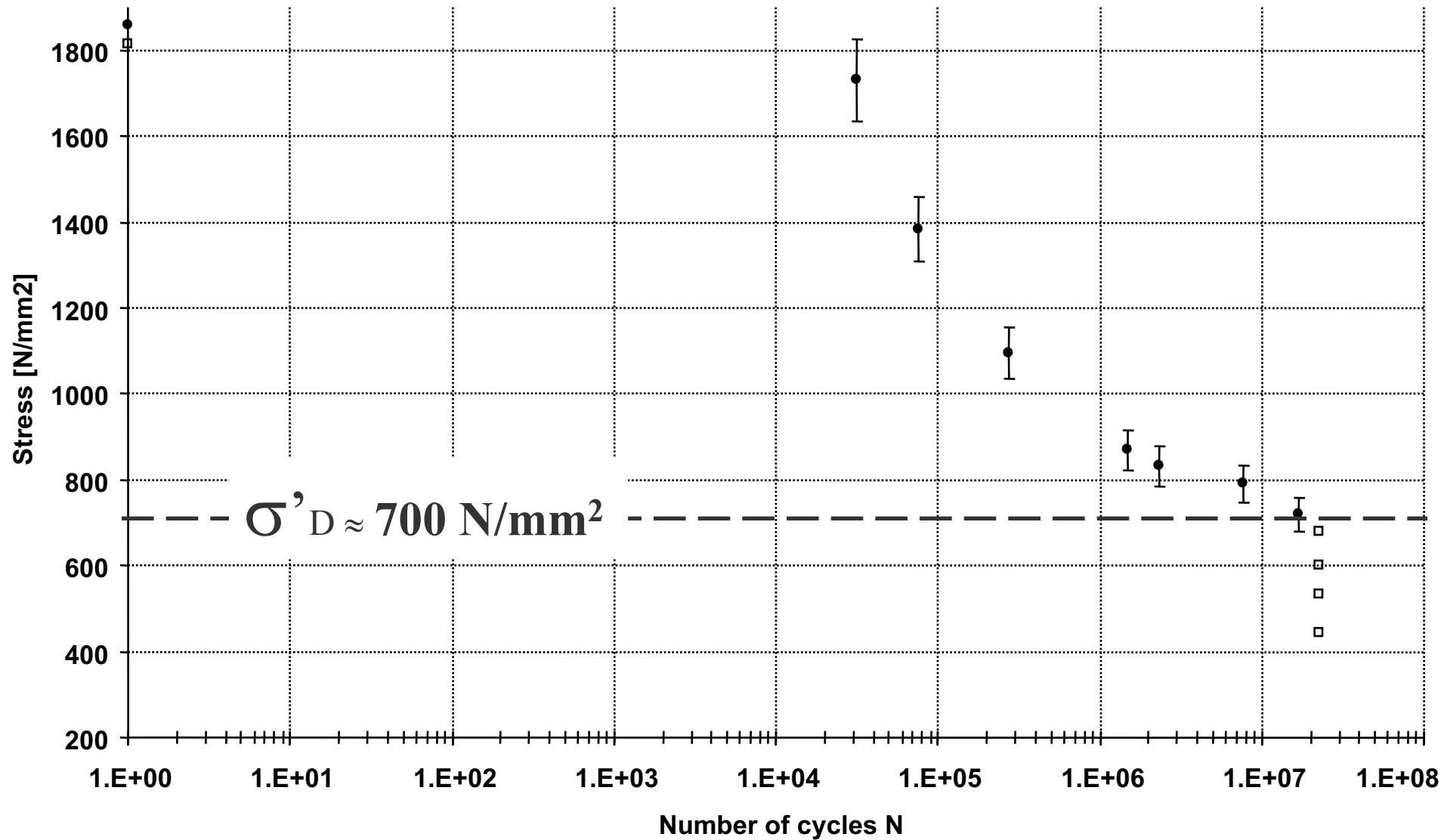
Example of fatigue test results

Bronze CN8, $R_a = 0.2 \mu\text{m}$



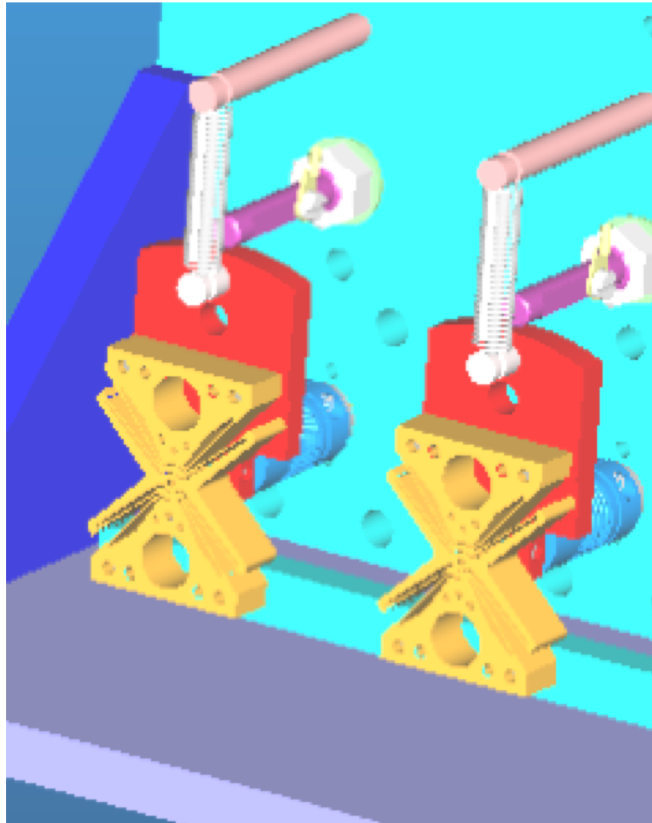
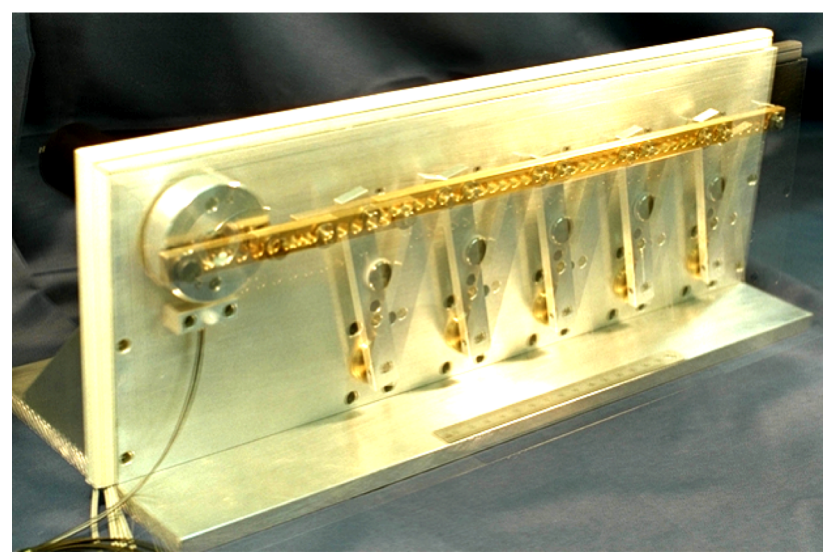
Example of fatigue test results

Steel W720, $Ra = 0.2 \mu m$

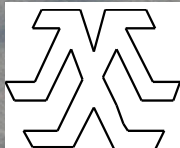


Fatigue tests on real parts

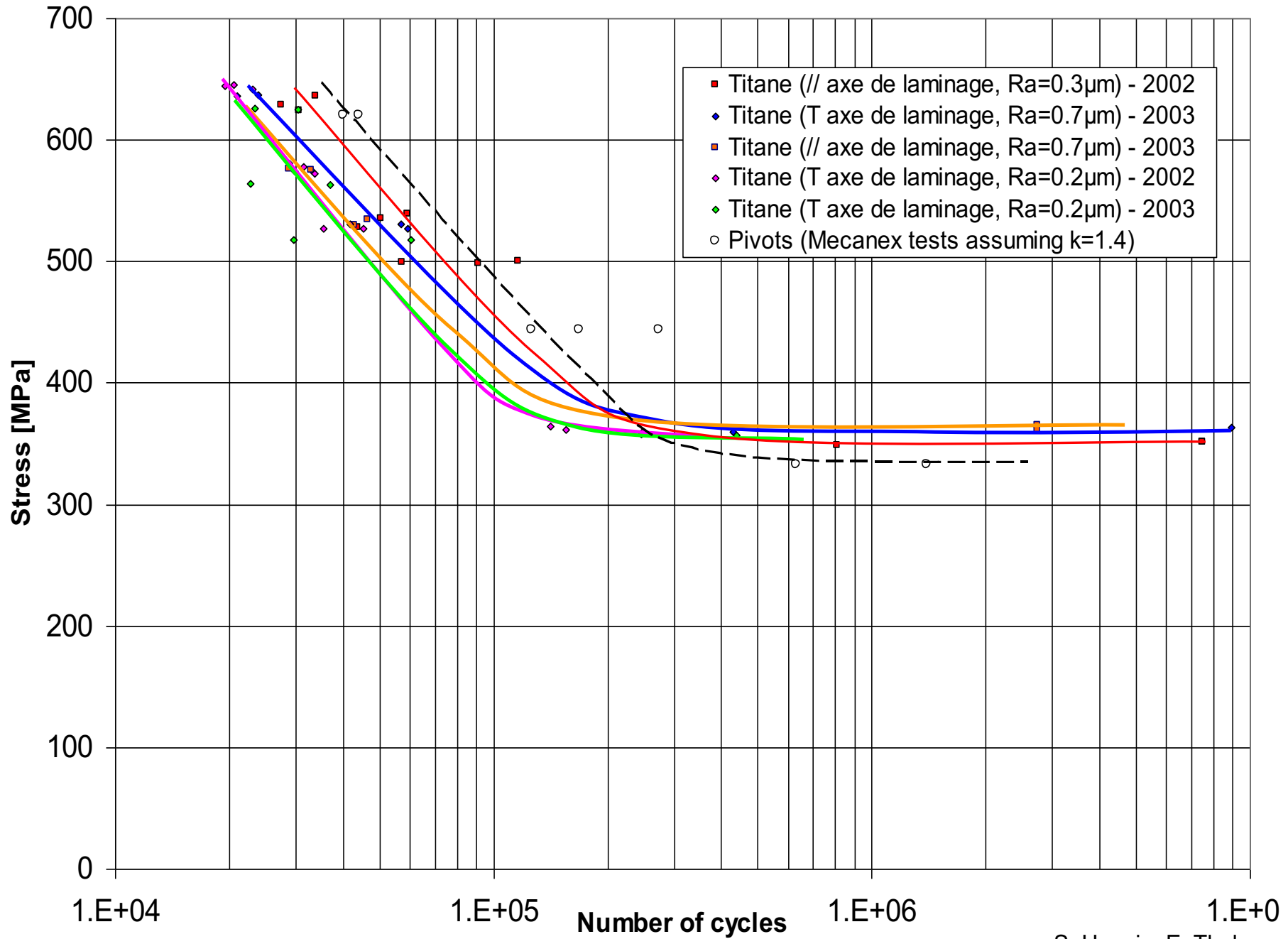
Example of the “Butterfly-Pivot”



MECANEX SA
Switzerland



Titanium (Ti-6Al-4V) fatigue tests

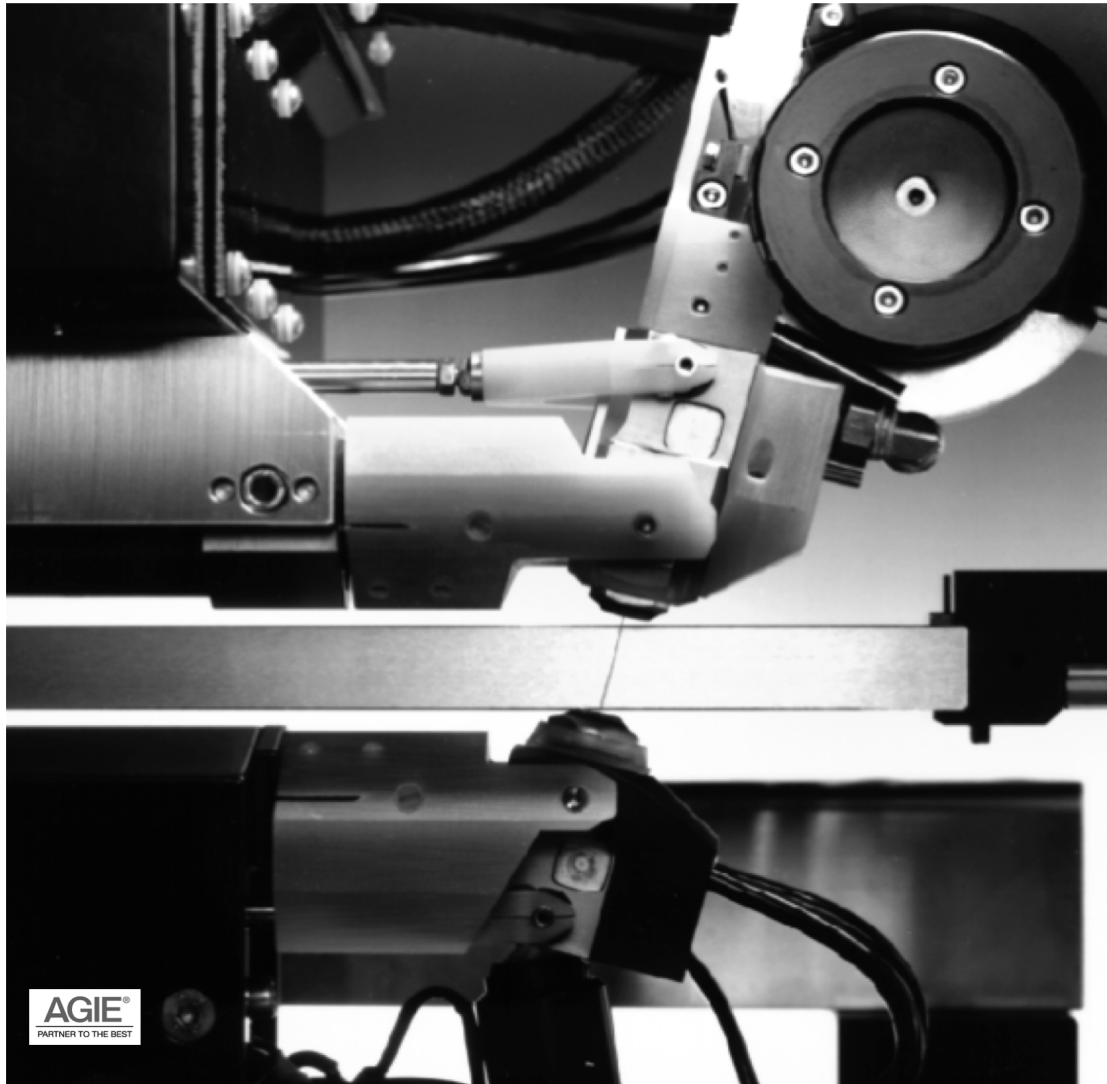


Conclusion of the fatigue experiments

- For roughnesses below $Ra=0.2\mu\text{m}$, the fatigue data derived from standard fatigue tests appear to be valid for thin (down to 30 microns) flexible hinges machined by wire-EDM.
- Increasing the roughness decreases the fatigue limit and increases uncertainties on the measured thicknesses and the calculated stress inside the flexures.
- For the most demanding applications (e.g. aerospace), fatigue testing of the real parts often cannot be avoided.

[Henein, S. et al. (1999), Fatigue failure of thin wire-EDM machined flexible hinges, *Proc. SPIE Int. Symp. on Intelligent Systems & Adv. Manufacturing*, Vol 3834, Boston, USA]

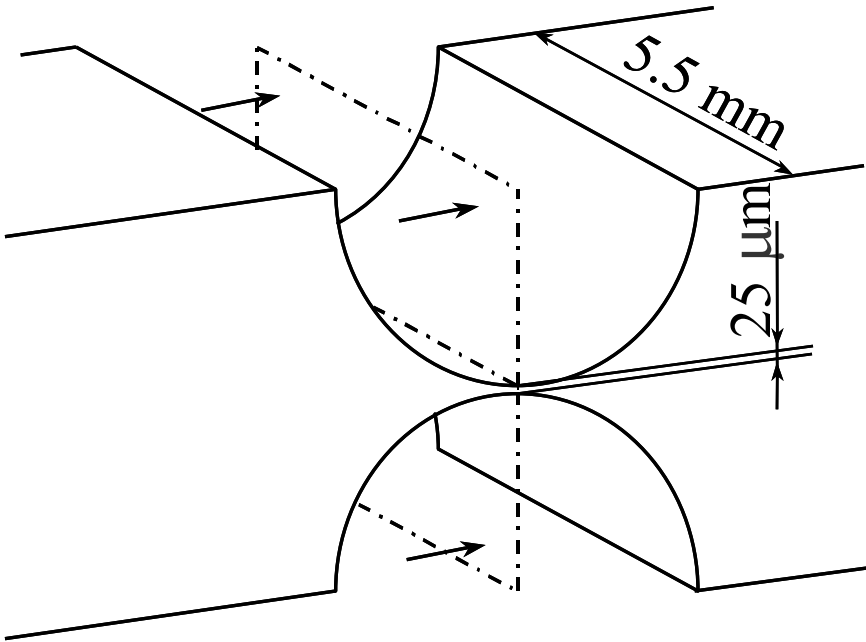
Wire electro-discharge machining

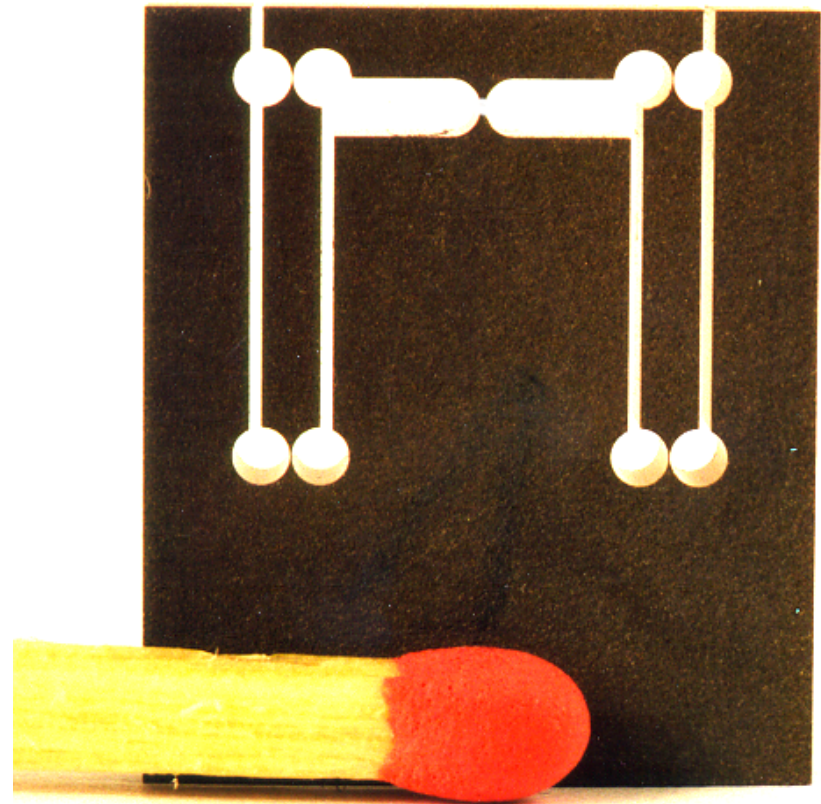


- Very small machining forces
- Insensitivity to hardness
- High aspect ratios
- High precision
- Monolithic machining



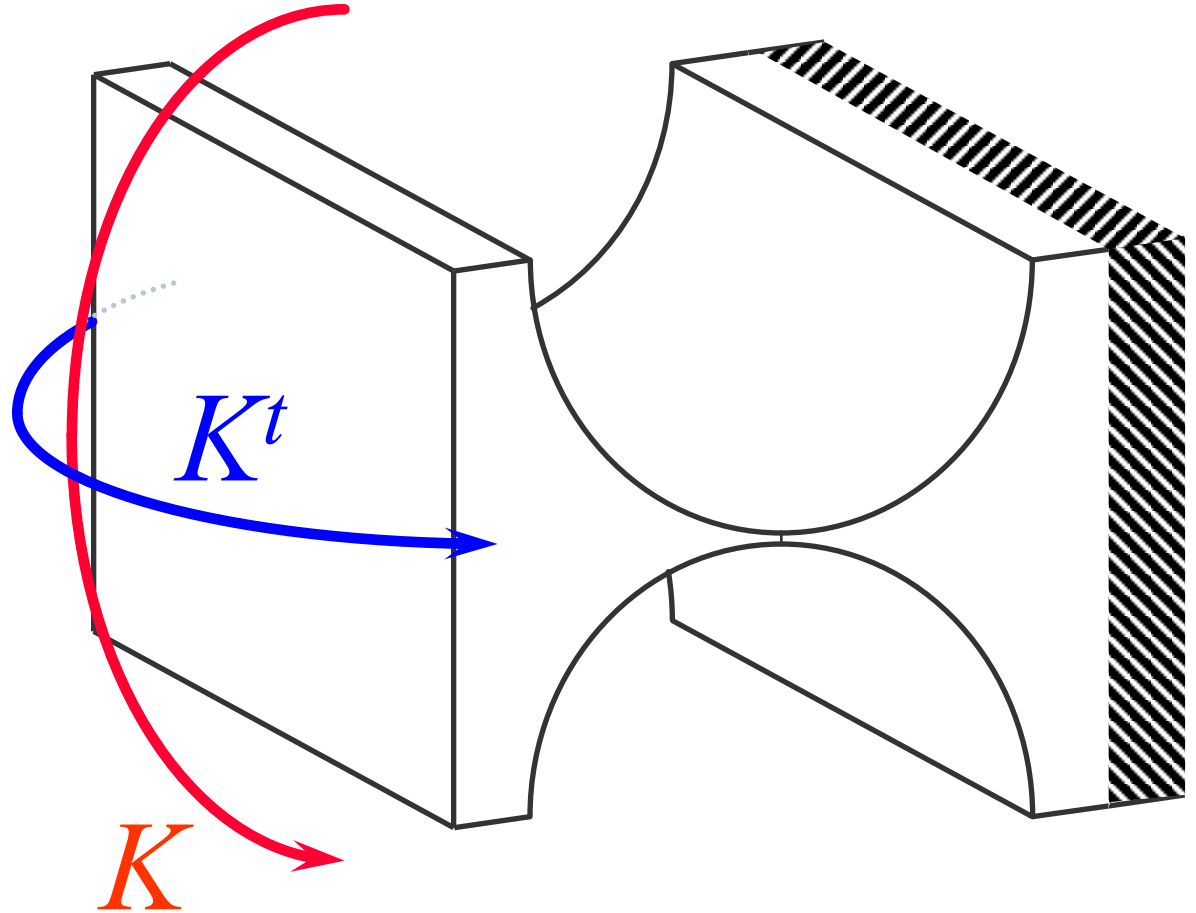
High Aspect Ratios





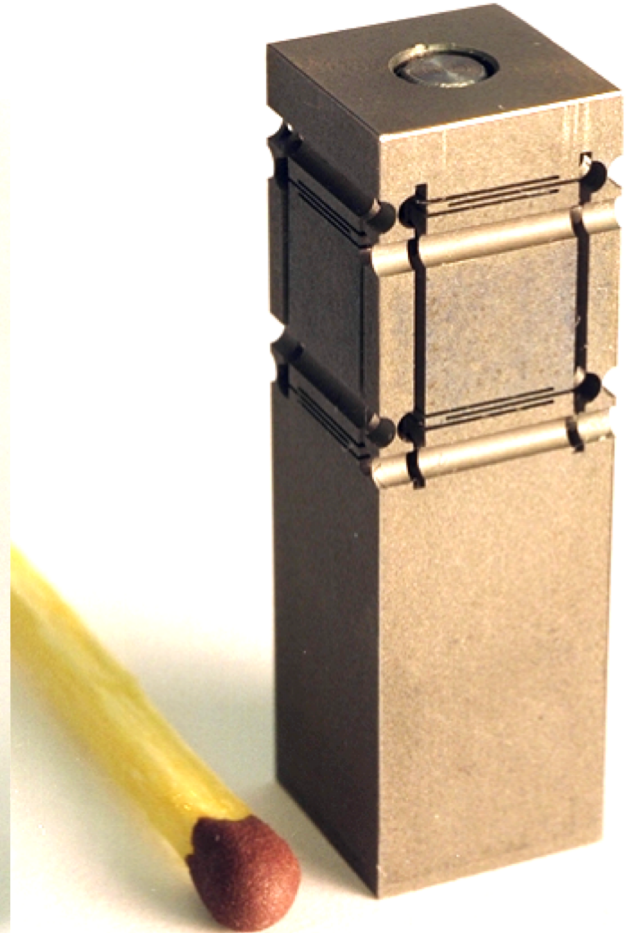
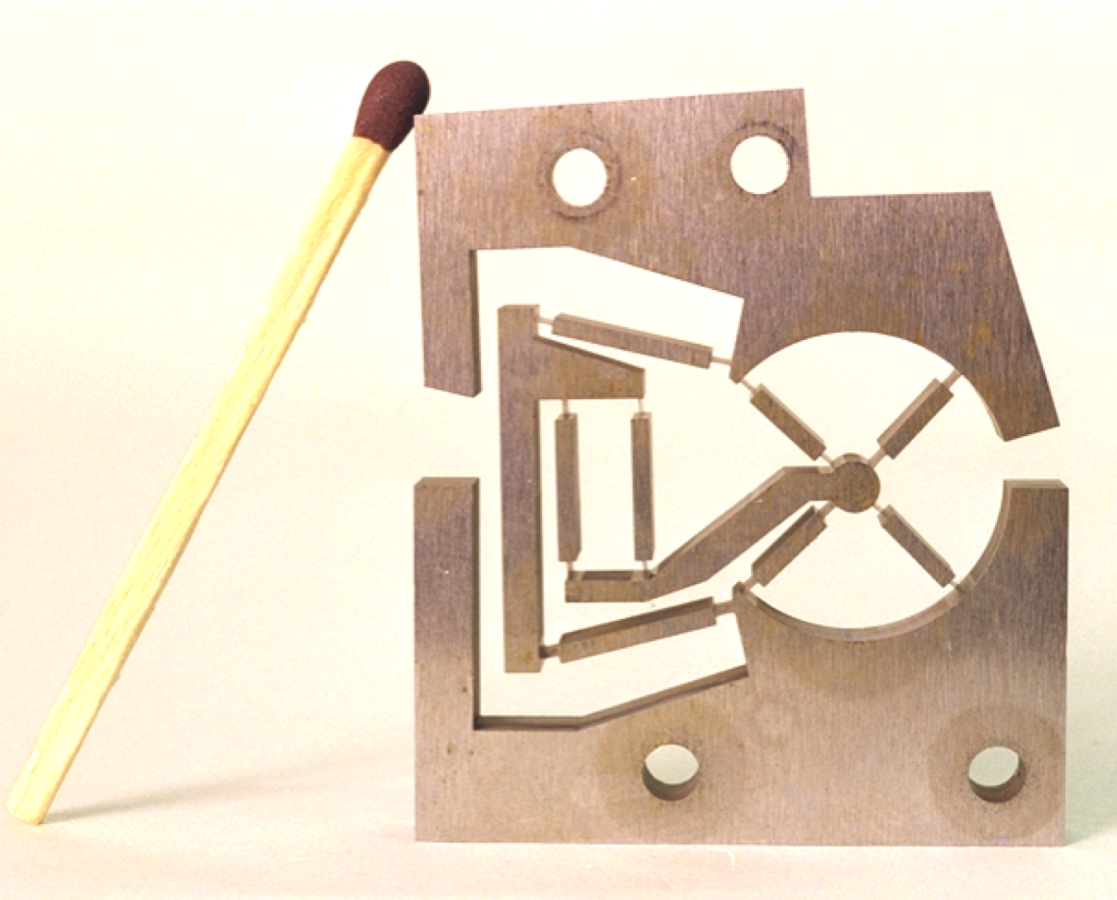
High Stiffness Ratios

$$\frac{K^t}{K} > 20'000$$



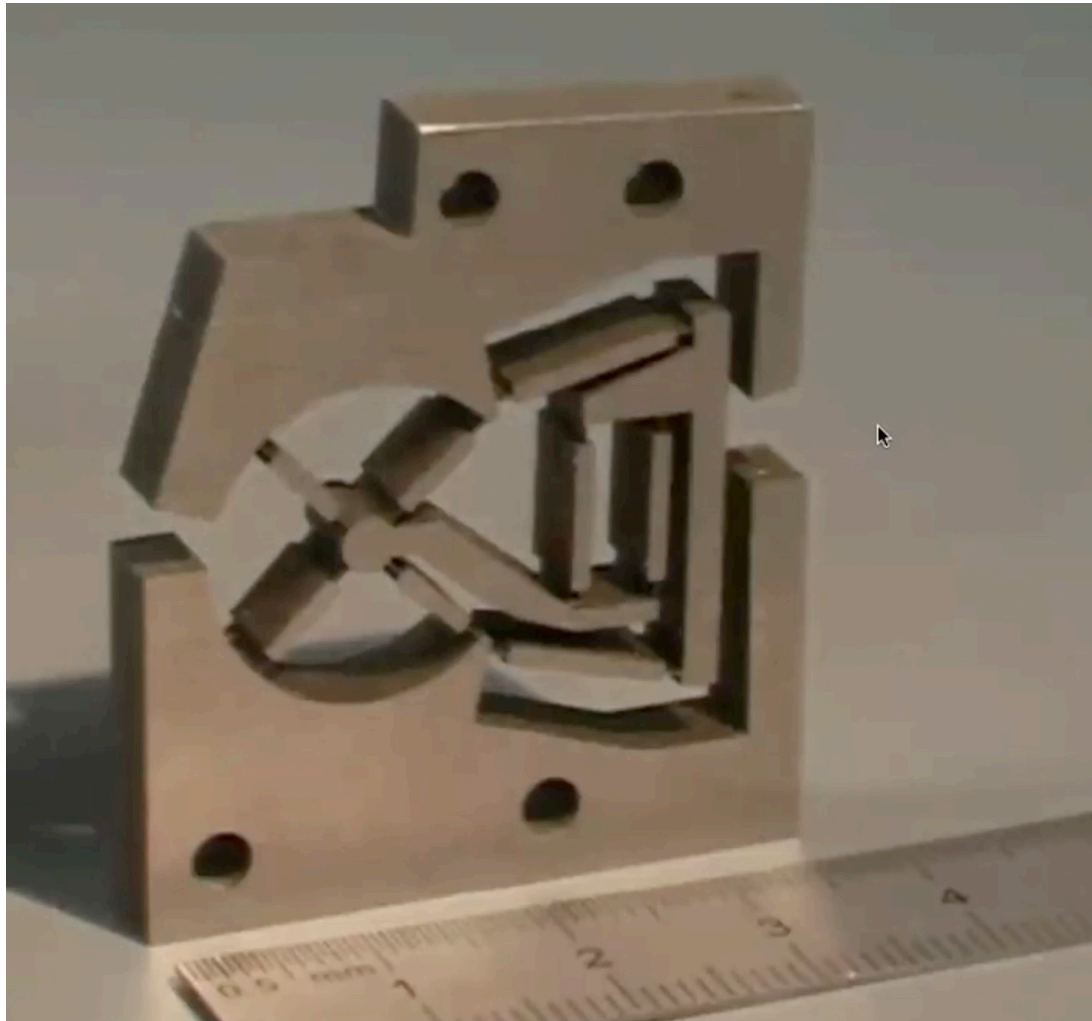
Monolithic manufacturing of complex structures

« Design for no assembly »



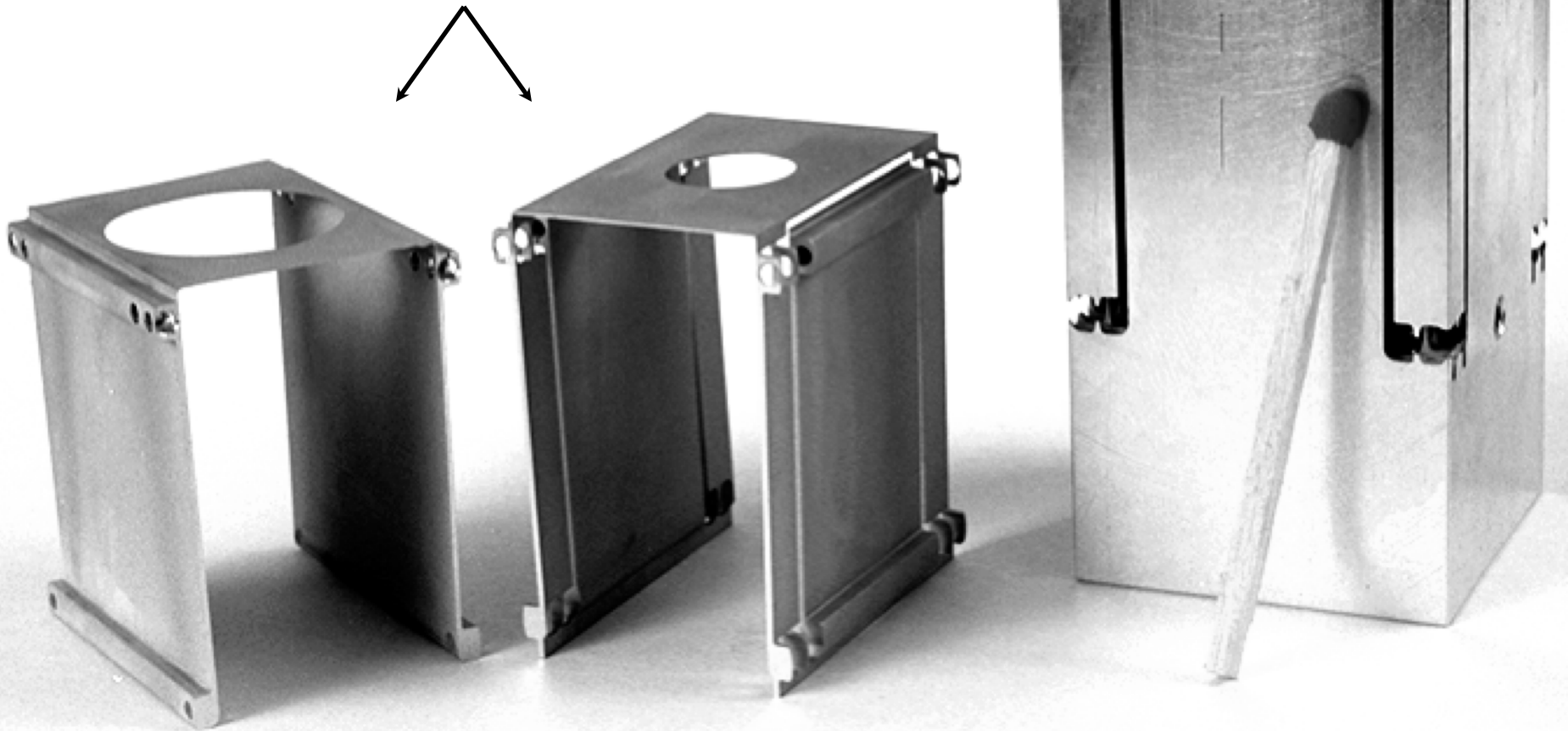
Monolithic flexure pivot

Serial notched RCC pivot with slaving mechanism



Monolithic manufacturing of complex structures

« Chips » removed from the bulk material
to produce the X-Y stage on the right.



Technological limitations of wire-EDM

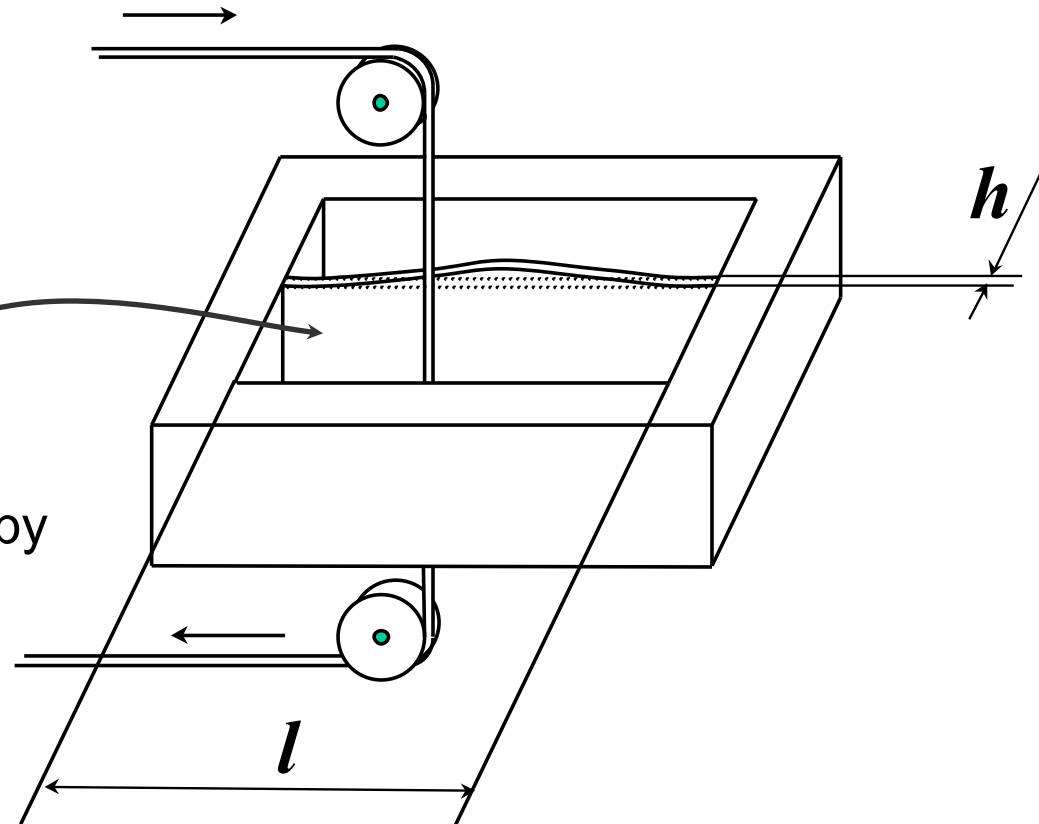
Maximum aspect-ratio of blades

We have experimentally demonstrated that the aspect-ratio of blades machined by wire-EDM is limited to approximately 60

$$\frac{l}{h} \leq 60$$

Vibrations of the blade induced by

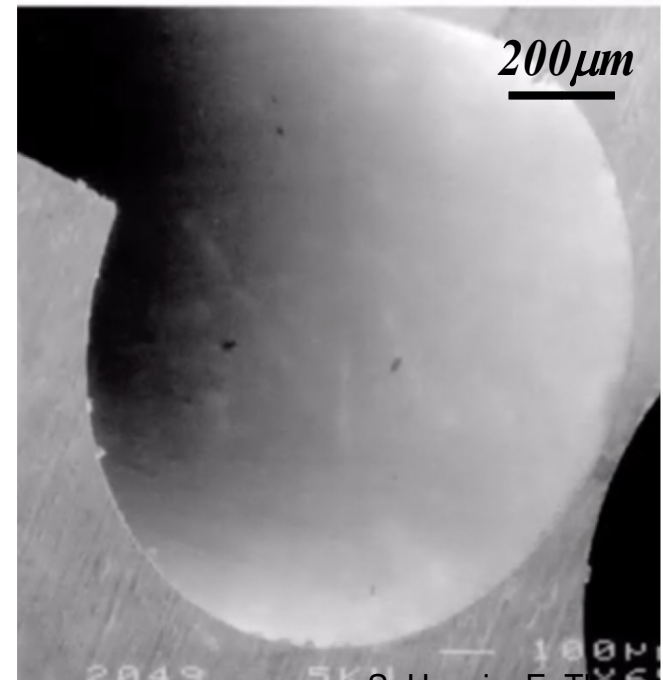
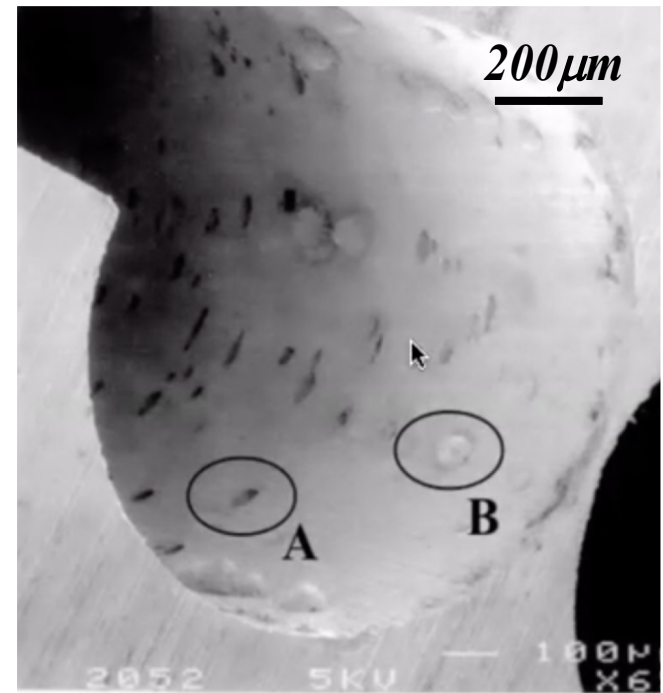
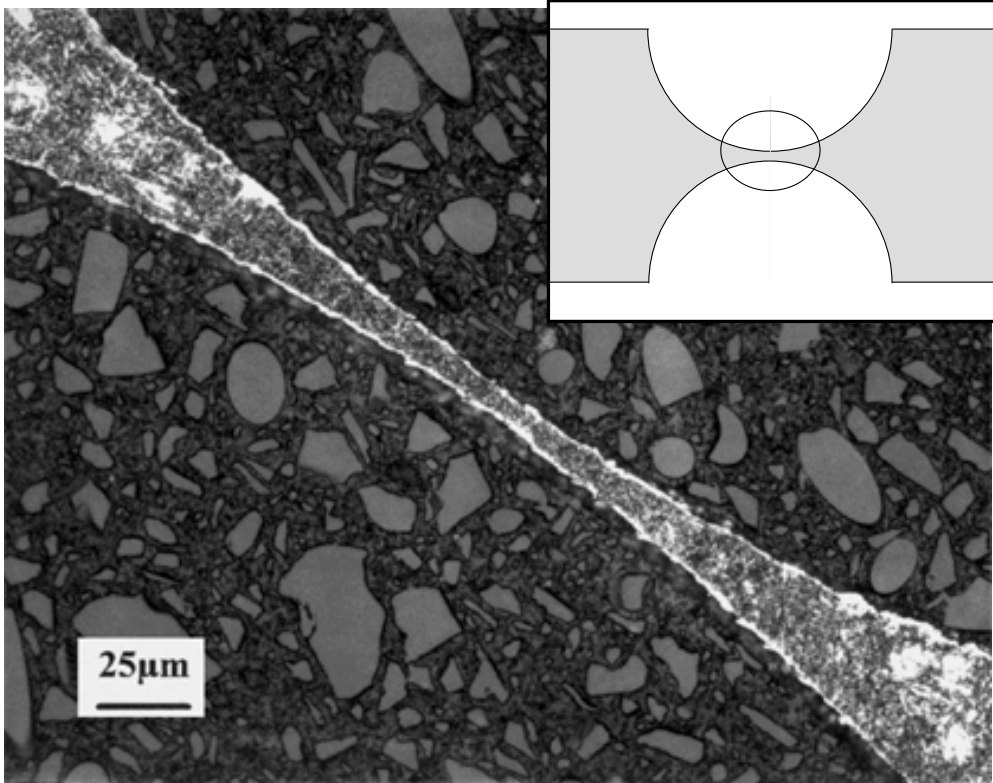
- jet of rinsing water
- electrical arcs and bursts
- electrostatic forces



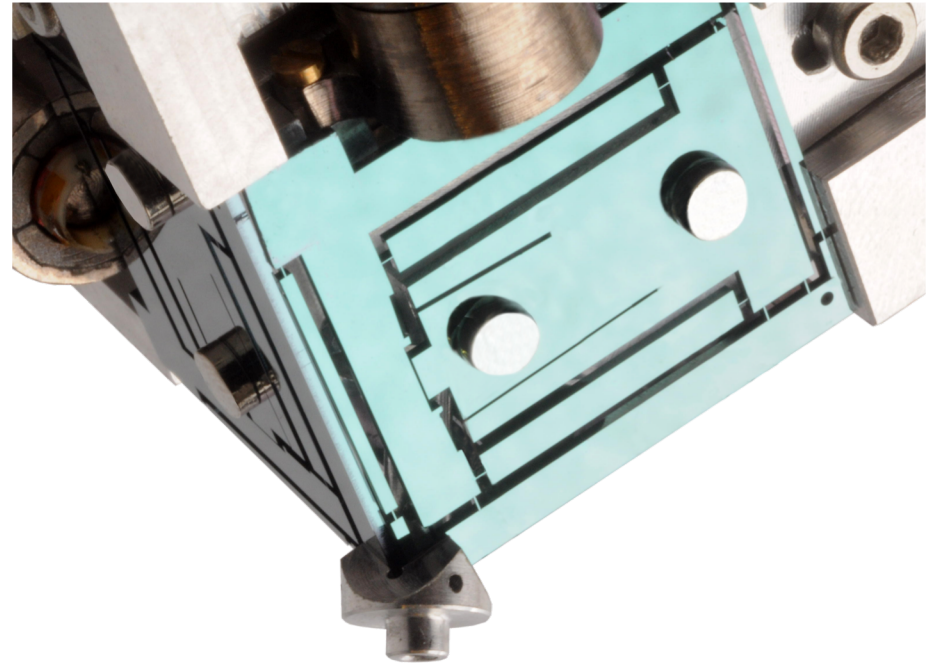
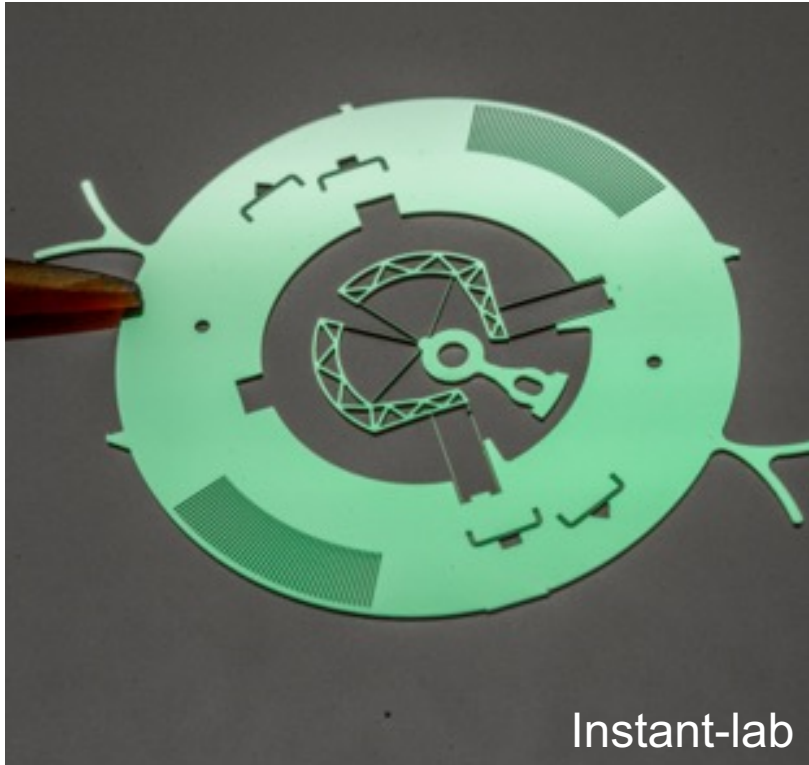
Technological limitations of wire-EDM

Minimum thickness: typically 30 μm

Best surface roughness: typically R_a 0.2 μm



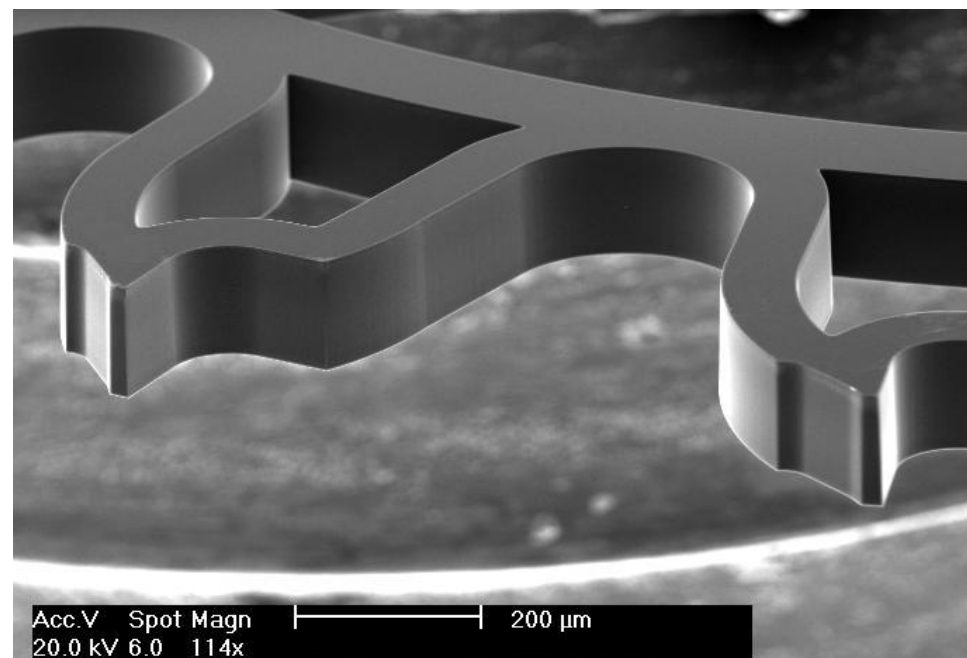
Flexures in Silicon



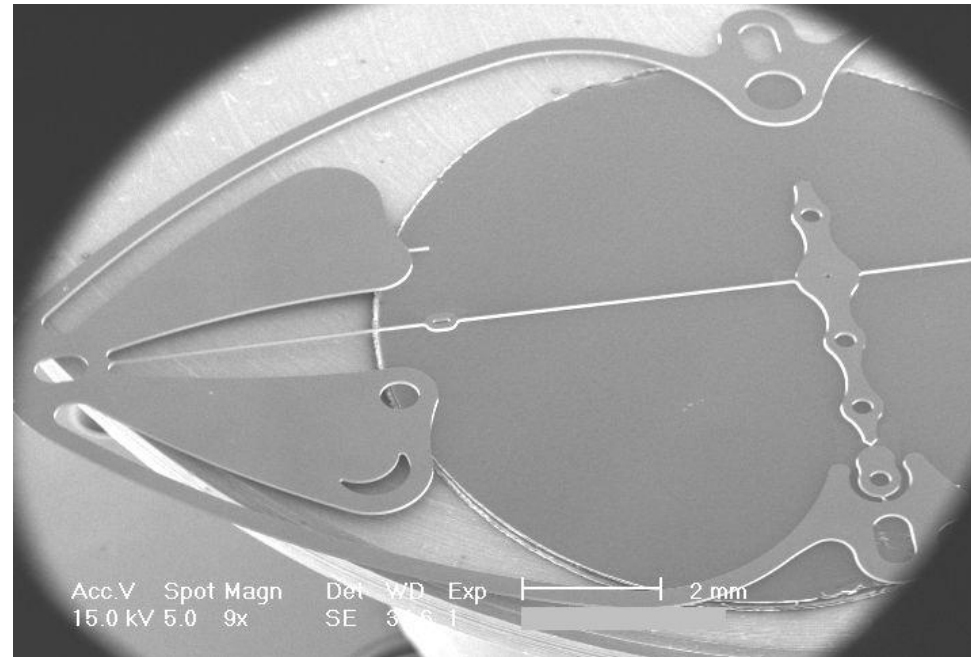
csem

Silicon parts for watches

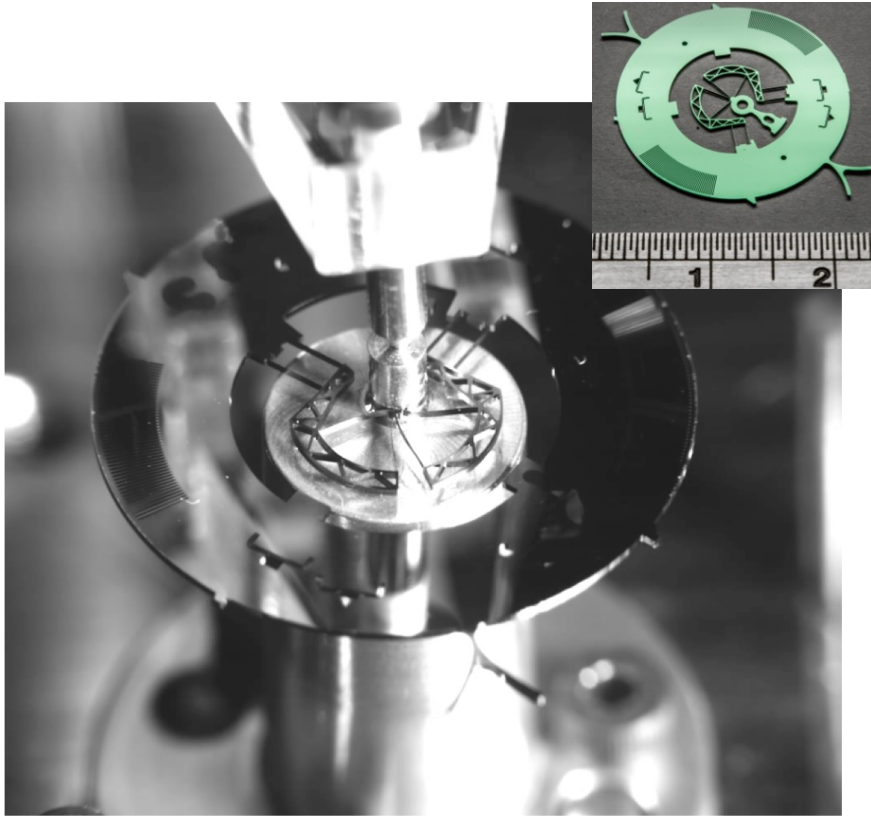
Escapment wheel (Ulysse Nardin)



Constant force escapment
(Girard-Perregaux)



Silicon flexure oscillators for watches



1- DOF «co-RCC» flexure oscillator



2- DOF «Wattwins» flexure oscillator

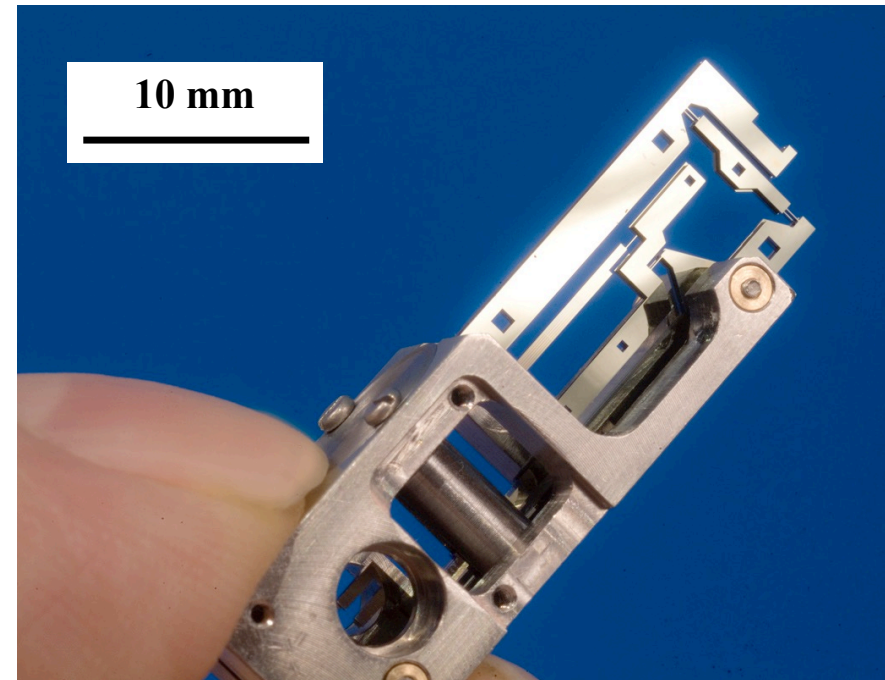
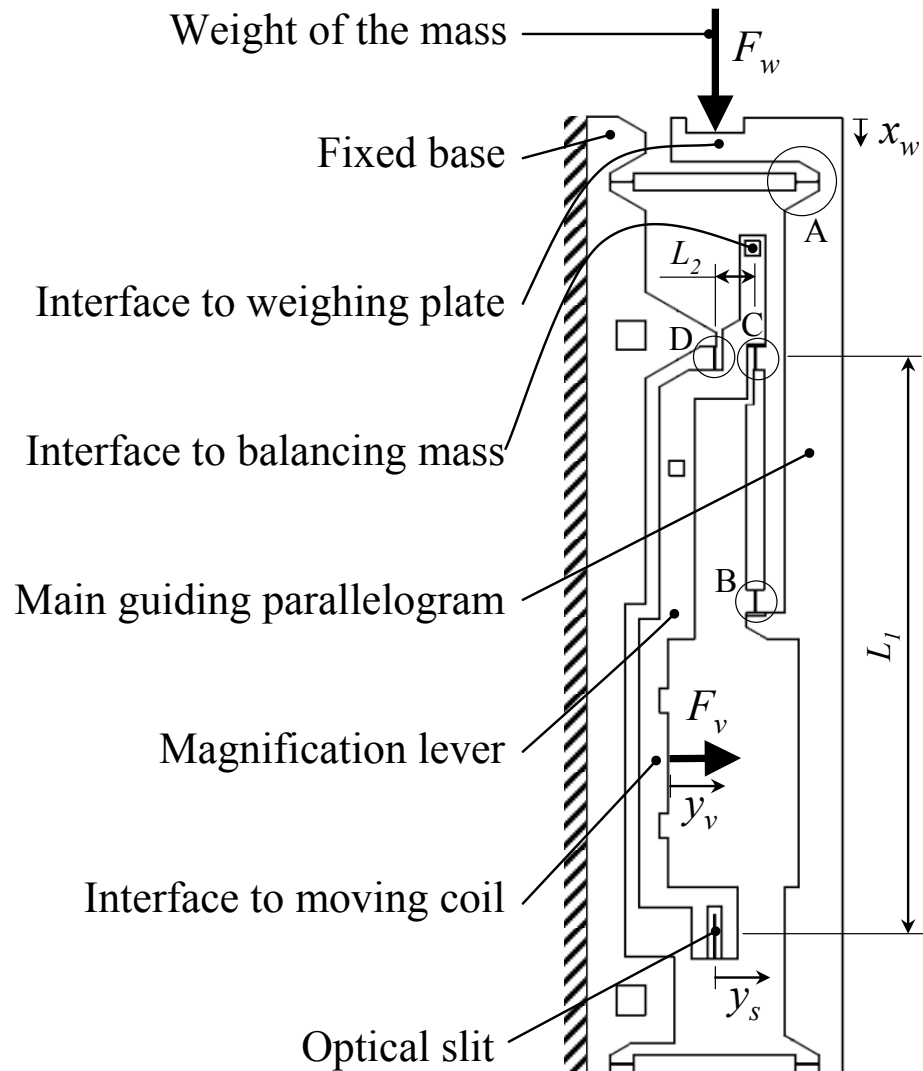
Thalmann, E. (2020). *Flexure Pivot Oscillators for Mechanical Watches* [EPFL]. <https://doi.org/10.5075/epfl-thesis-8802>

Schneegans, H., Thalmann, E., & Henein, S. (2021). Shaking force balancing of a 2-DOF isotropic horological oscillator.

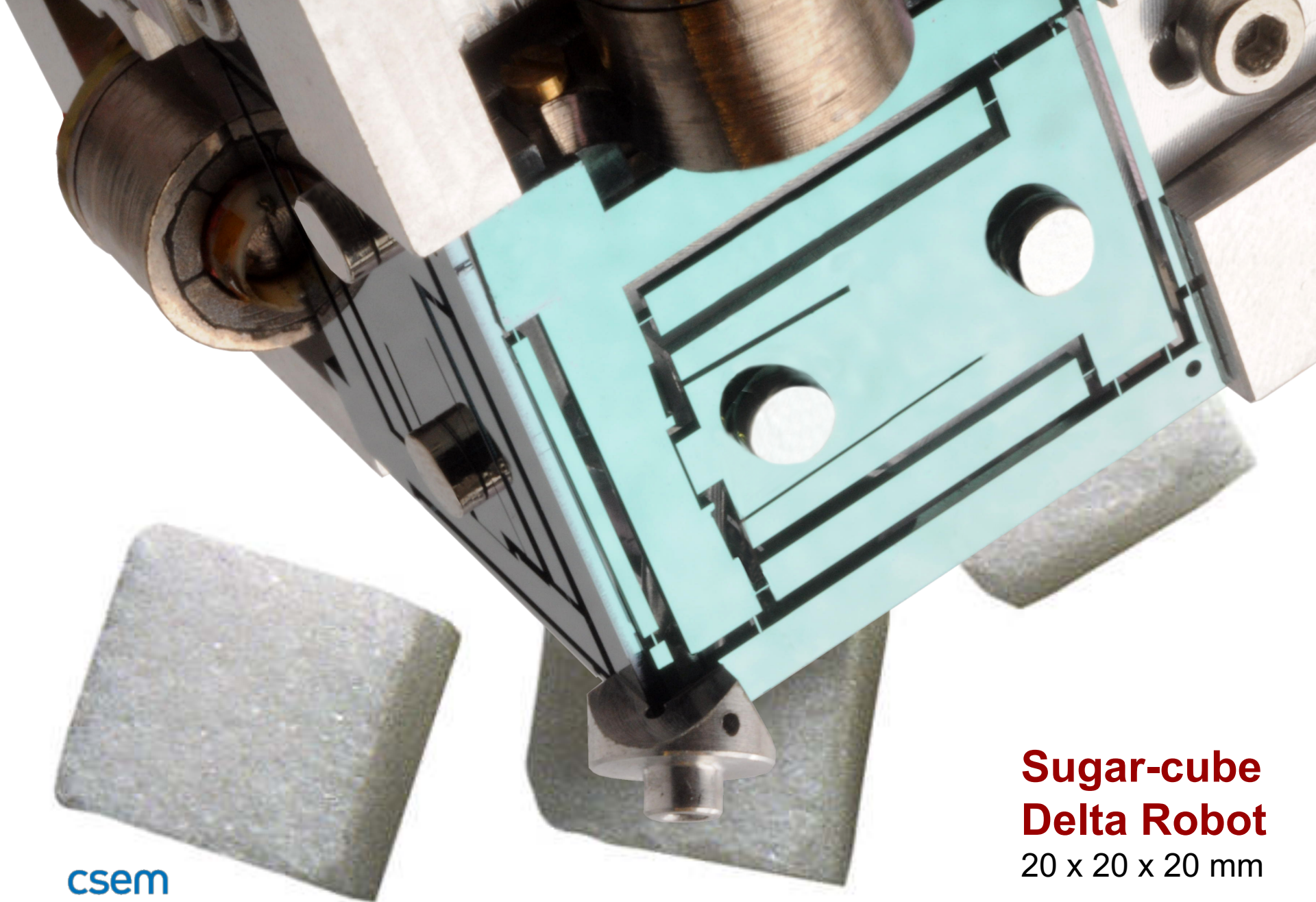
Precision Engineering, 72,

Silicon flexure-based micro-balance

Footprint 9 x 9 mm, suitable for batch weighing processes



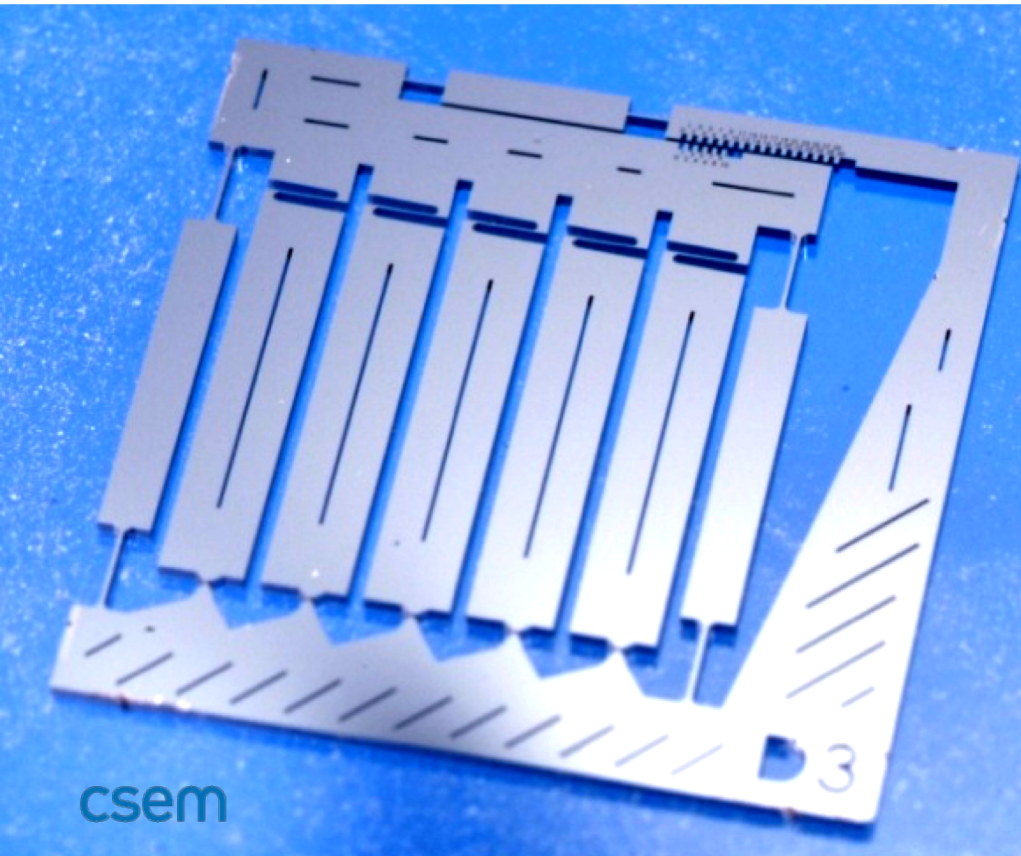
csem



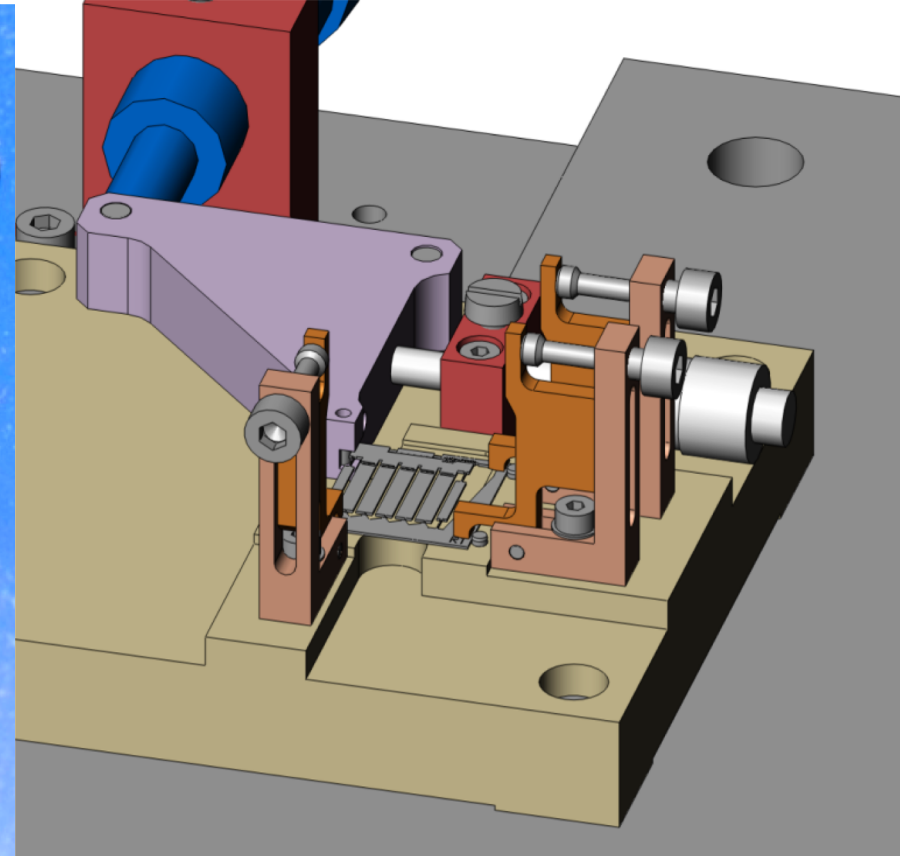
csem

**Sugar-cube
Delta Robot**
20 x 20 x 20 mm

Fatigue tests on silicon flexures

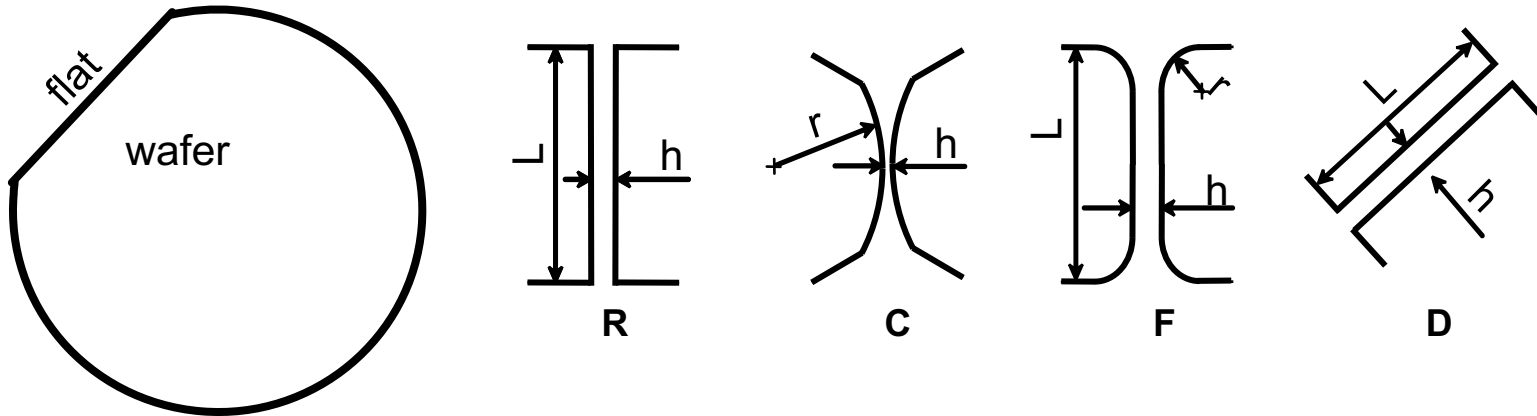


Test specimen



Test bench

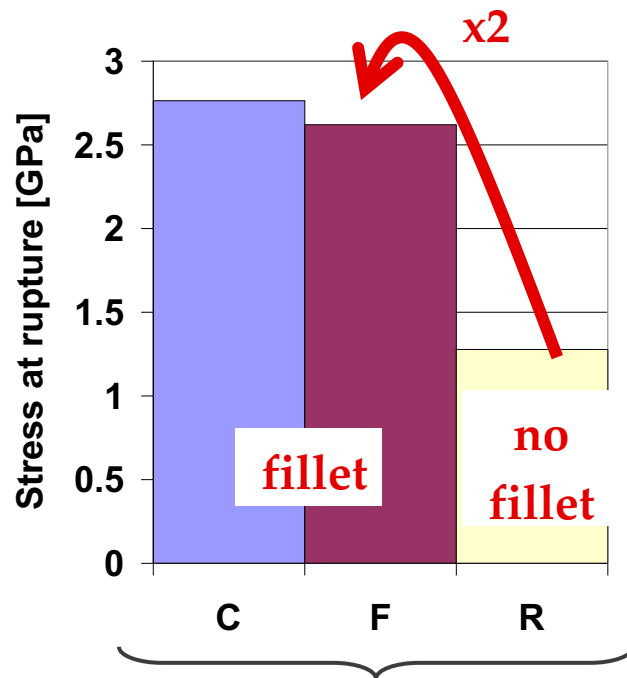
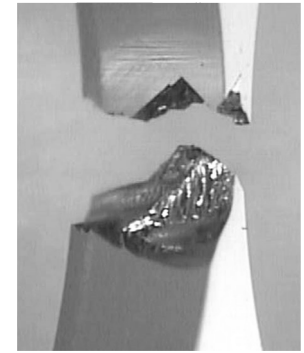
Tested hinge shapes and orientations



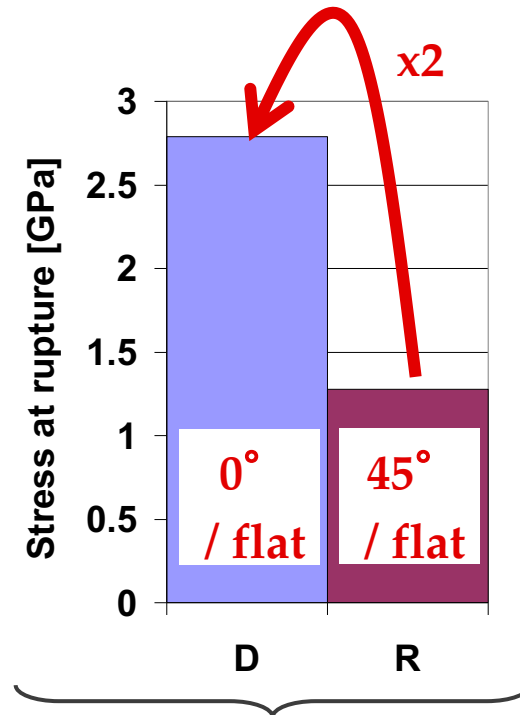
Orientation of tested hinges with respect to the wafer flat

Shape	h [μm]	b [μm]	r [μm]	L [μm]	Number of hinges
C	20 to 100	250 and 350	230 to 1150	-	103
D	10 to 50	250 and 350	-	40 to 200	41
F	10 to 100	250 and 350	10 to 100	40 to 400	116
R	50 to 100	250 and 350	-	200 to 400	73

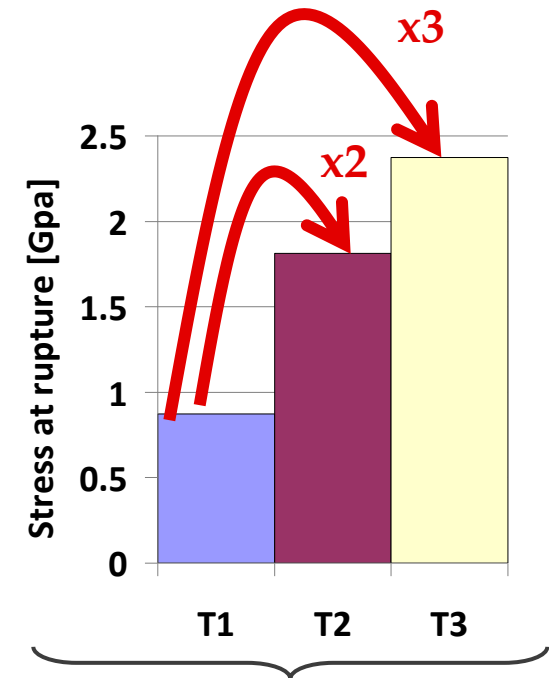
Synthetic Results of the Fracture Tests



- . same orientation w.r.t. the crystal lattice
- . with or without fillet

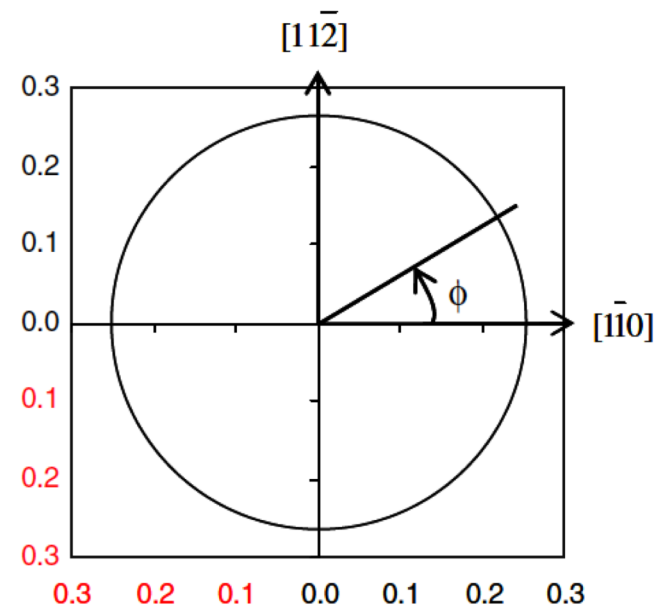
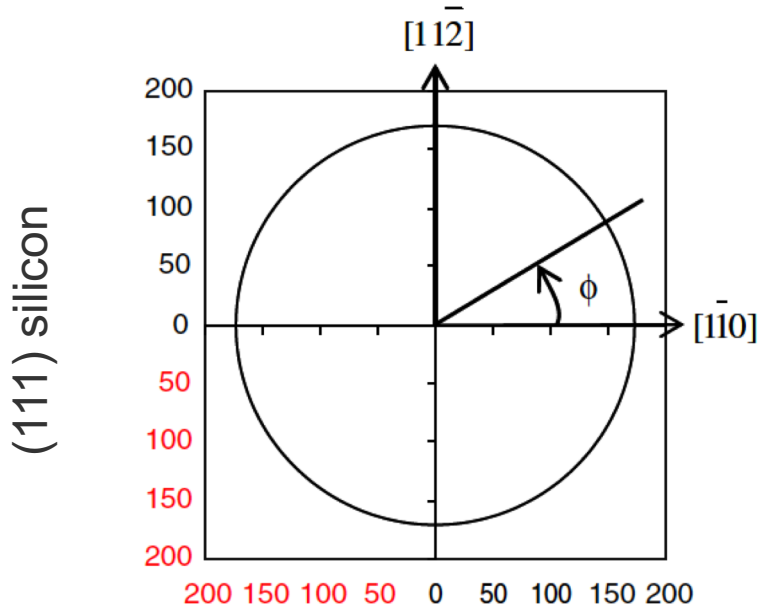
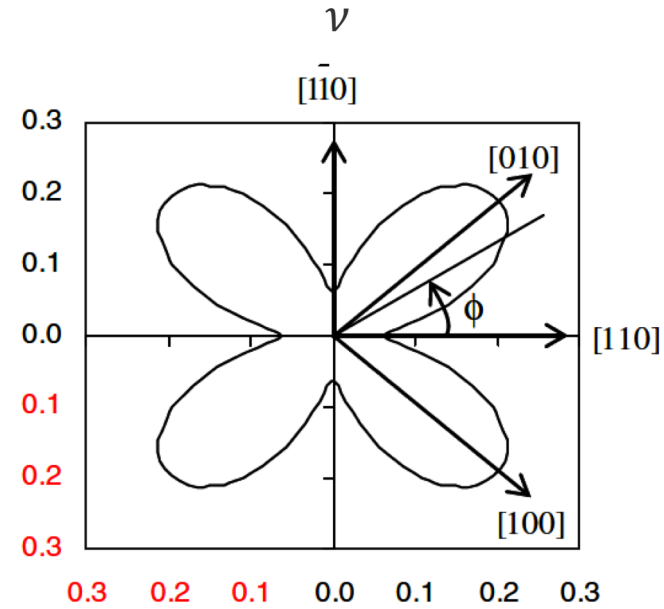
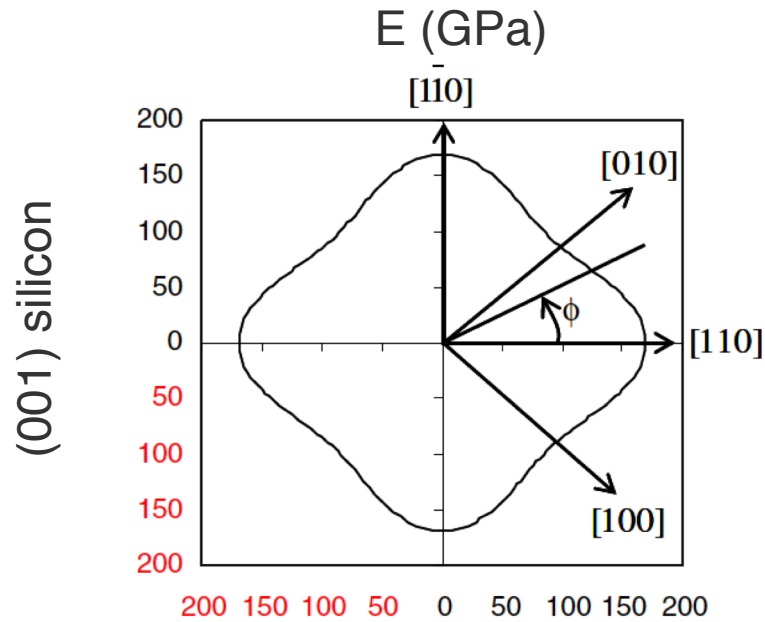


- . same shape
- . different orientations w.r.t. the crystal lattice

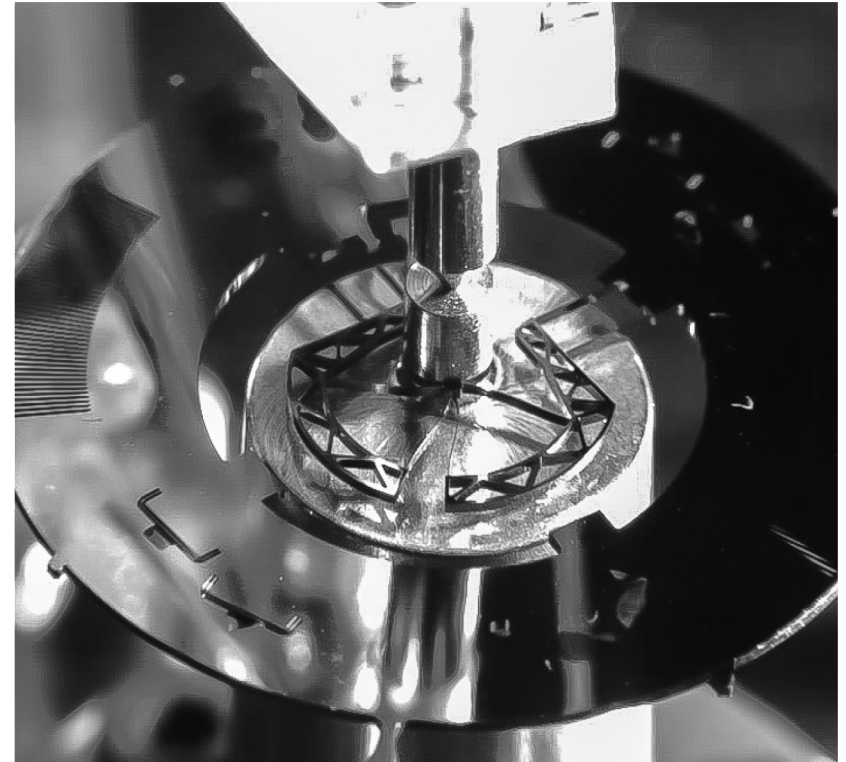
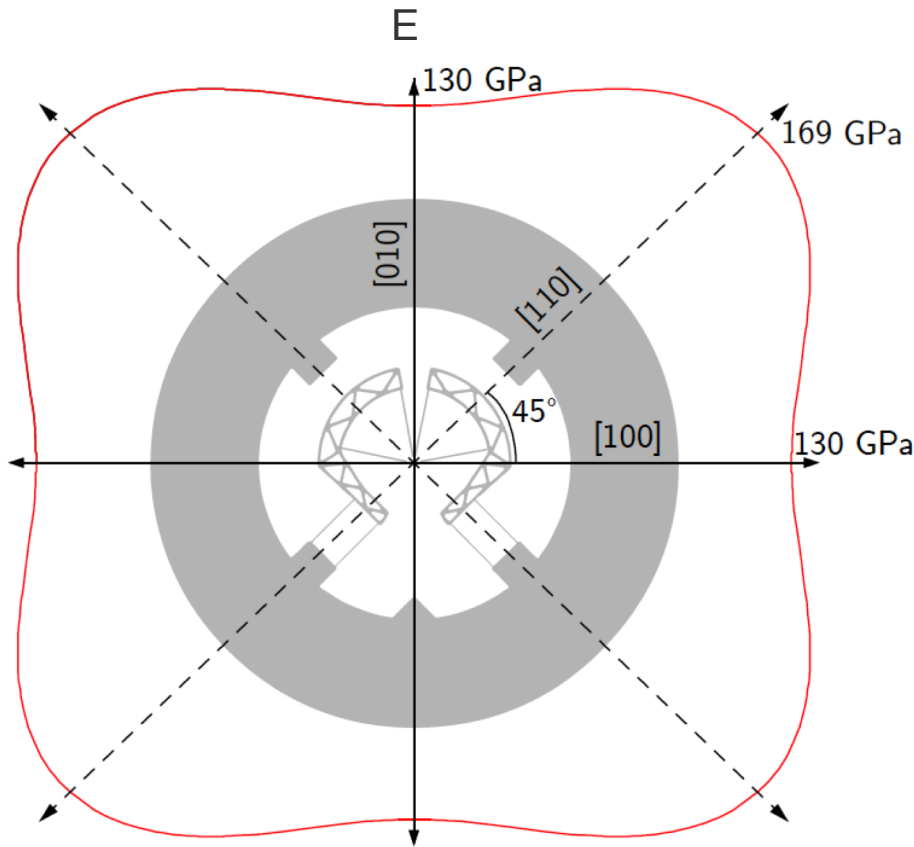


- . different surface treatment

Anisotropy of silicon

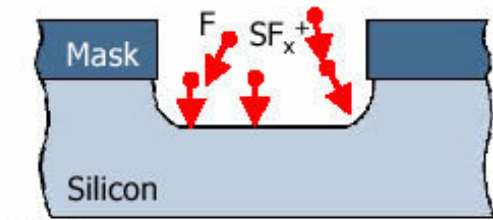


Taking anisotropy into account for design

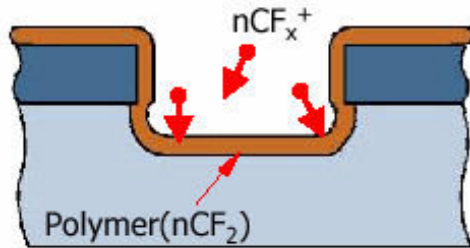


Thalmann, E. (2020). *Flexure Pivot Oscillators for Mechanical Watches* [EPFL Thesis].

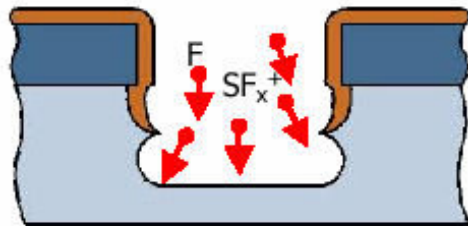
DRIE



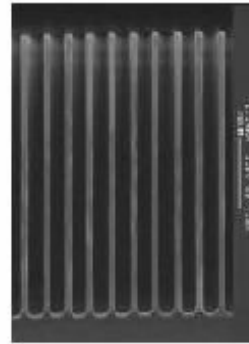
Etch



Deposit Polymer



Etch



Trenches - Surface Technology Systems



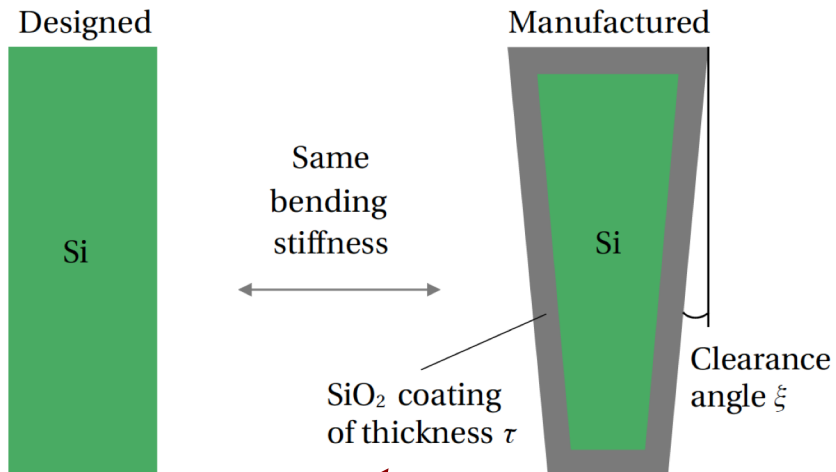
Spring - Klaassen, et al, 1995

- High aspect ratios (b/h and L/h)
- High precision
- Micro-scale
- Monolithic fabrication
- Batch manufacturing
- ⚠ Scalloping
- ⚠ Clearance angle

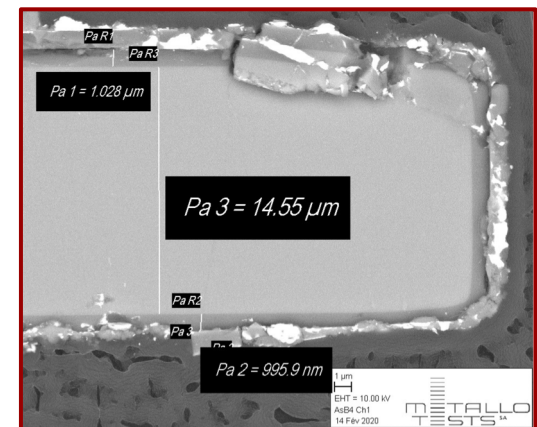
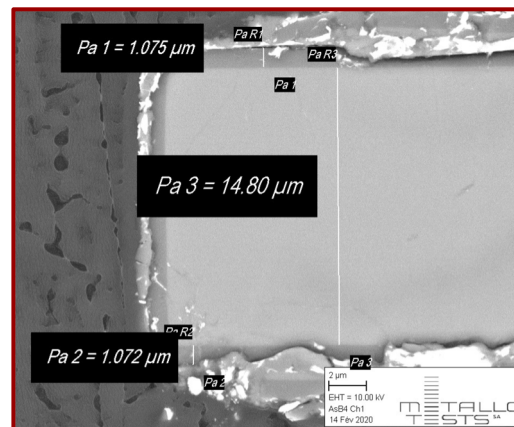
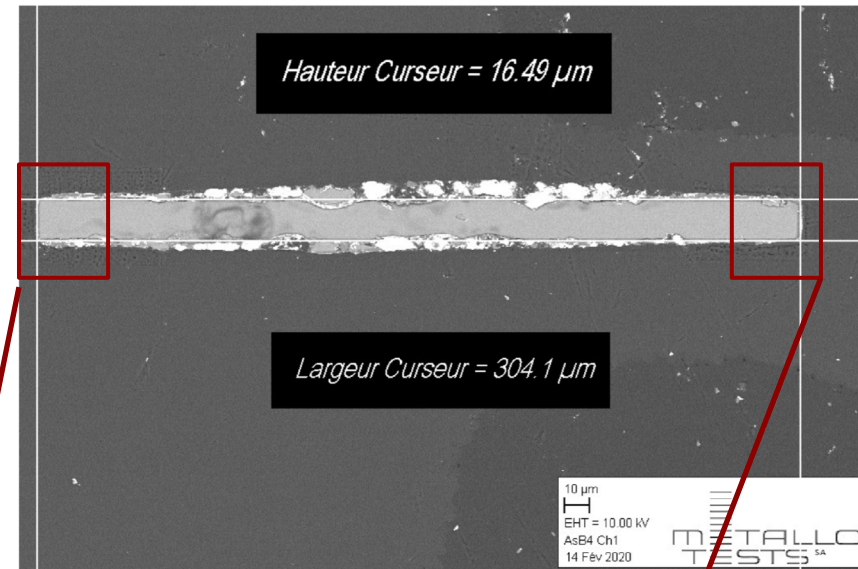
https://www.researchgate.net/figure/Deep-Reactive-Ion-Etching-Microfabrication-Process-2_fig2_242139877

Taking into account clearance angle and oxide layer

$$E_{\text{Si}} I_{\text{rect}} = E_{\text{Si}} I_{\text{Si}} + E_{\text{ox}} I_{\text{ox}}$$



Thermal compensation



Thalmann, E. (2020). *Flexure Pivot Oscillators for Mechanical Watches* [EPFL Thesis].
 Musy, J.-P., Maier, F., & Kr  tli, A. (2008). *Echappement et spiral r  alis  s en Silinvar  *.
 Journ  e d'Etude de la SSC 2008.

Mechanical properties of silicon

Comparison with steel

	Si	Steel	Units
Thermal expansion coefficient	2.6	12.0	$10^{-6} / \text{K}$
Density	2.33	8	g/cm^3
Young's Modulus (E)	170*	210	GPa
Poisson coefficient	0.42*	0.30	
Shear coefficient	67*	80	GPa
Micro-hardness	~1200*	300-1000	kg/mm^2
Maximal stress	1000-2500*	500-2000	MPa

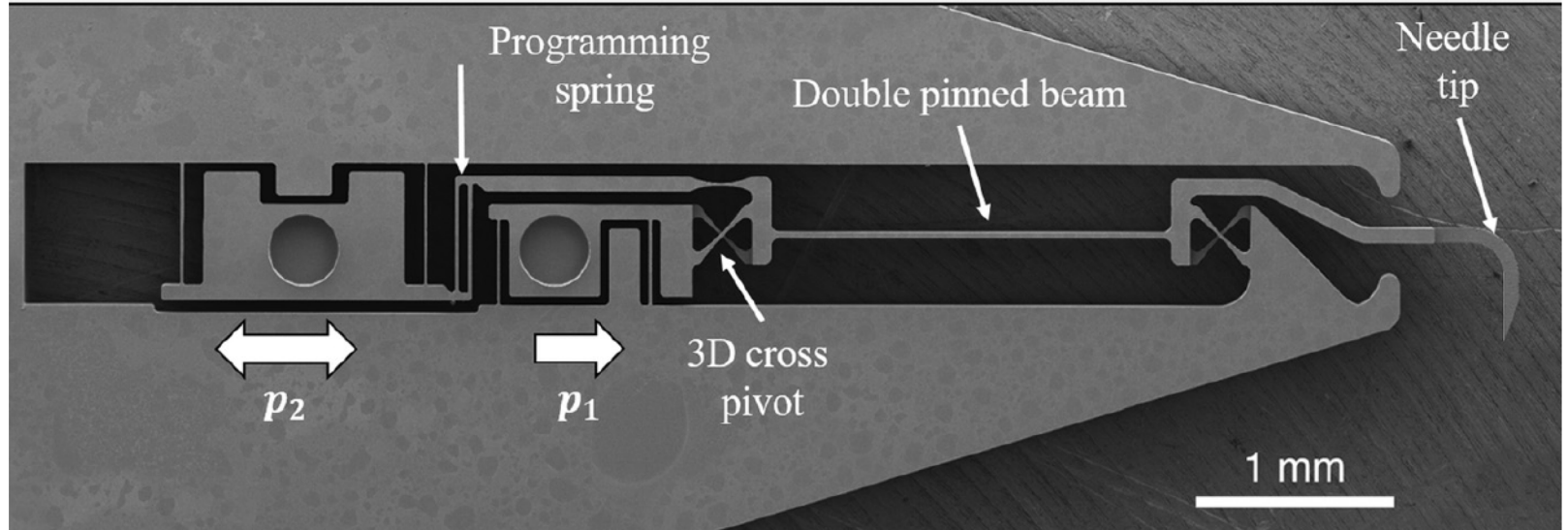
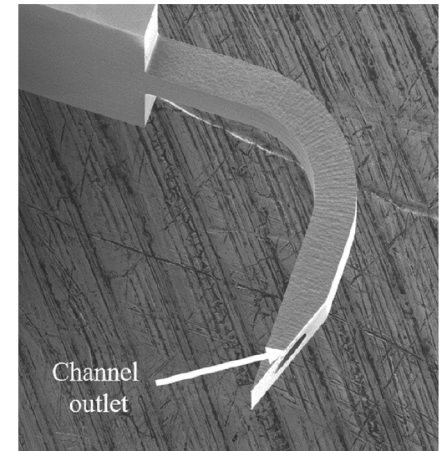
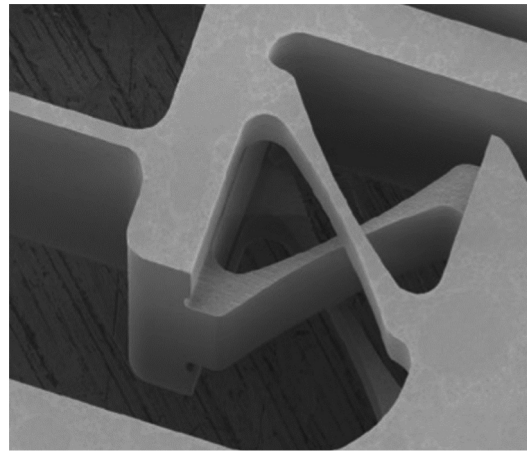
*** values depending on the crystalline orientation**

Flexures in glass

Femto-laser etching

Min flexure thickness $\approx 20 \mu m$

Tolerance on thickness: $\pm 2 \mu m$

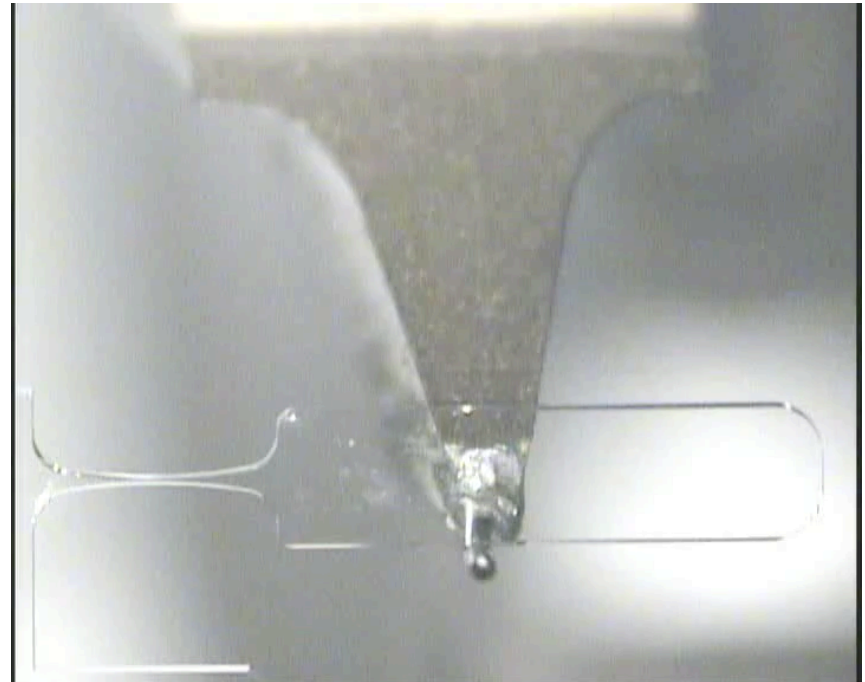


Zanaty, M., Fussinger, T., Rogg, A., Lovera, A., Lambelet, D., Vardi, I., Wolfensberger, T. J., Baur, C., & Henein, S. (2019). Programmable Multistable Mechanisms for Safe Surgical Puncturing. *Journal of Medical Devices*, 13(2), 021002.

Material properties

Fused silica

- $E = 74 \text{ GPa}$
- $\sigma_{adm} \approx 1 \text{ GPa}$
- $\nu = 0.17$
- $\rho = 2200 \text{ kg/m}^3$



Bellouard, Y. (2011). On the bending strength of fused silica flexures fabricated by ultrafast lasers. *Optical Materials Express*, 1(5)

Technological aspects : summary

- Wire-EDM
 - Maximum aspect-ratio ≈ 60
 - Effect of roughness on fatigue and stiffness
- Silicon : “Macro-MEMS” (2D-2.5D)
- Glass : Promising new material (3D structures).

